

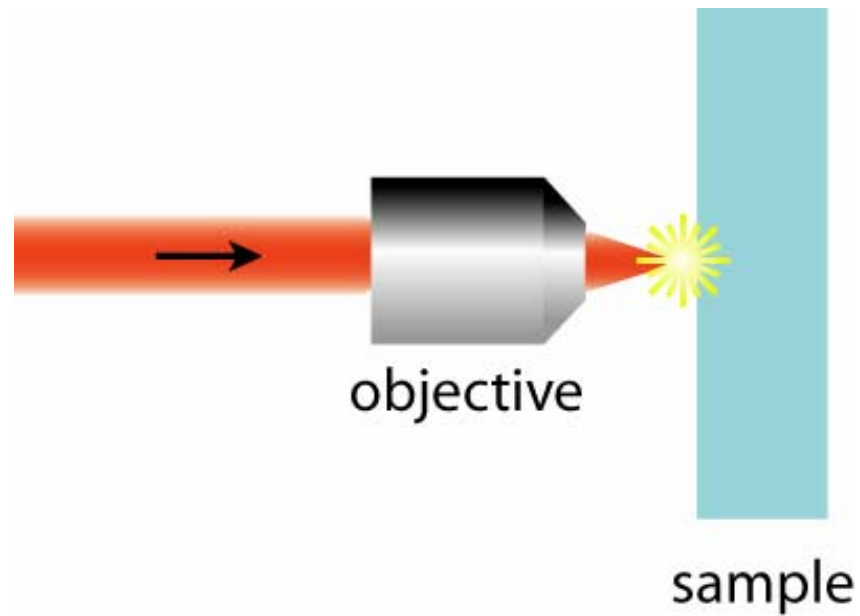
Part 2: fs-laser microfabrication

Prof. Dr. Cleber R. Mendonca

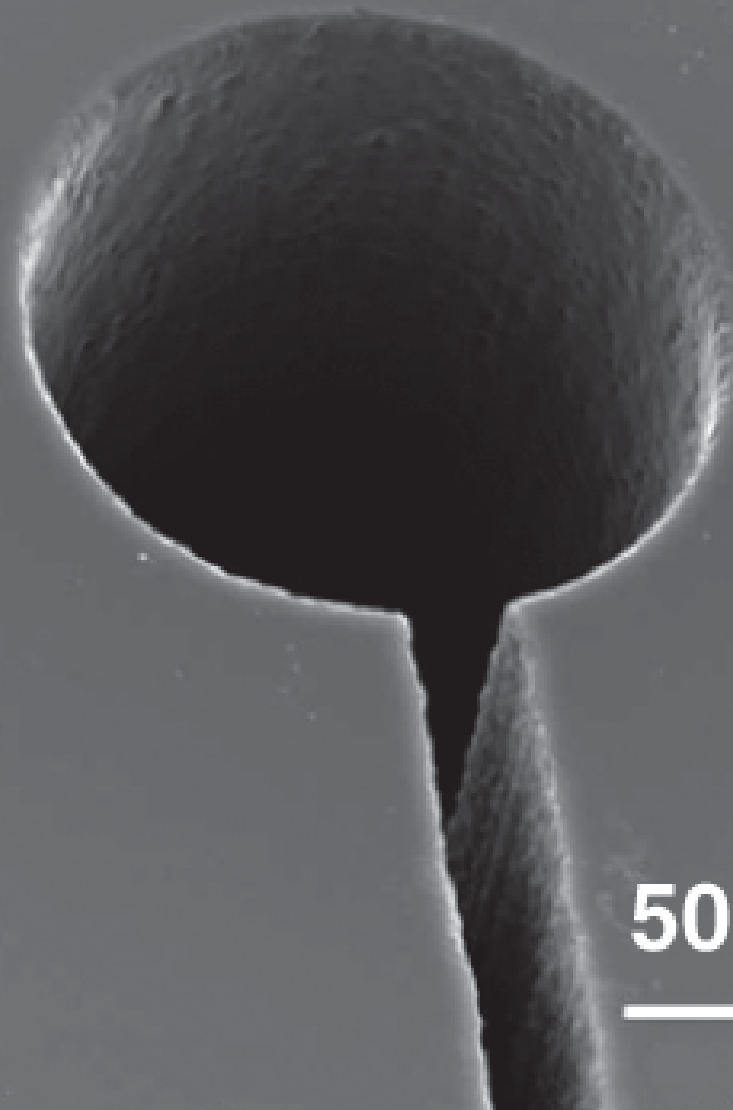


laser microfabrication

focus laser beam on material's surface



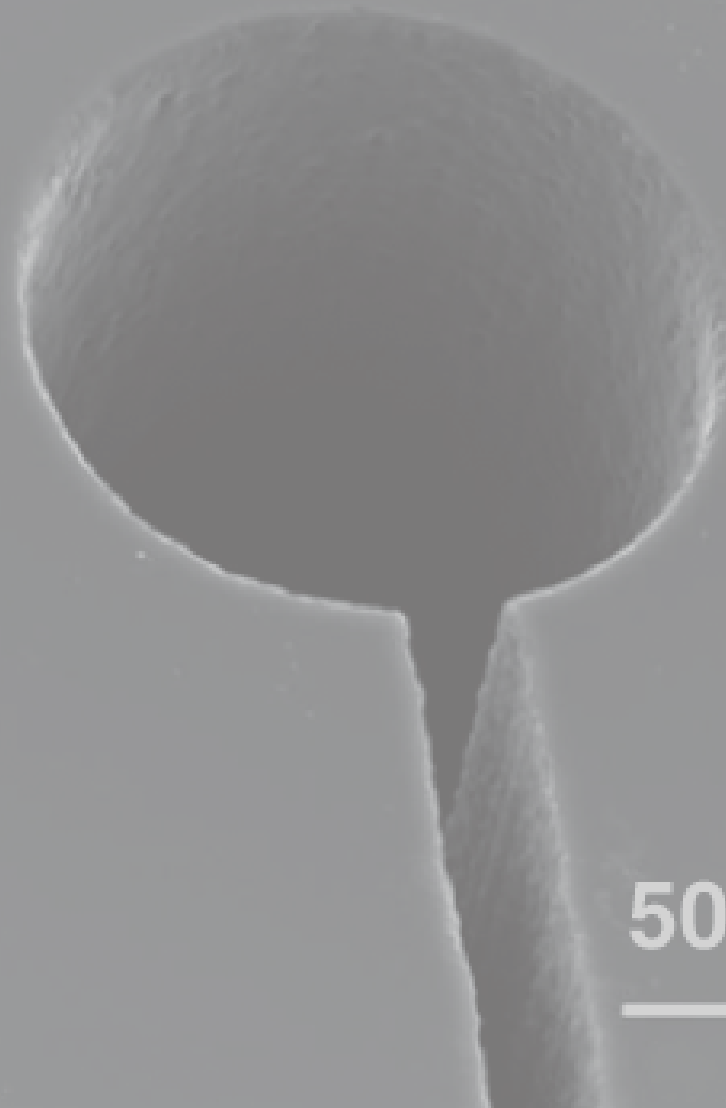
laser microfabrication



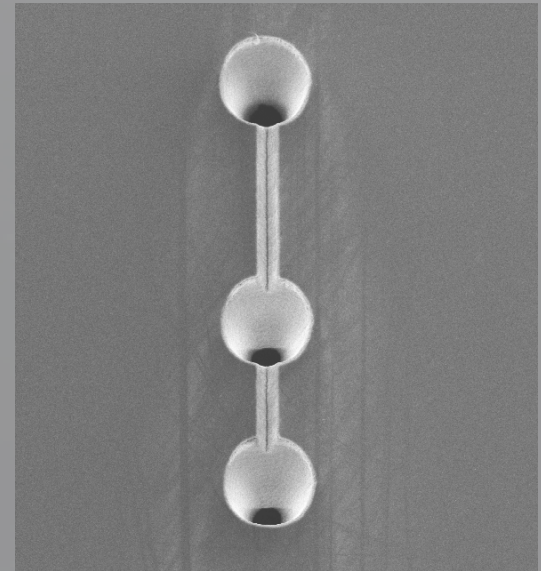
50 μm



laser microfabrication



50 μm

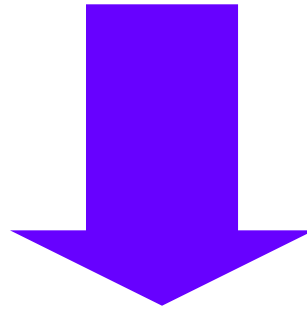


laser microfabrication

surface microstructuring

fs-micromachining

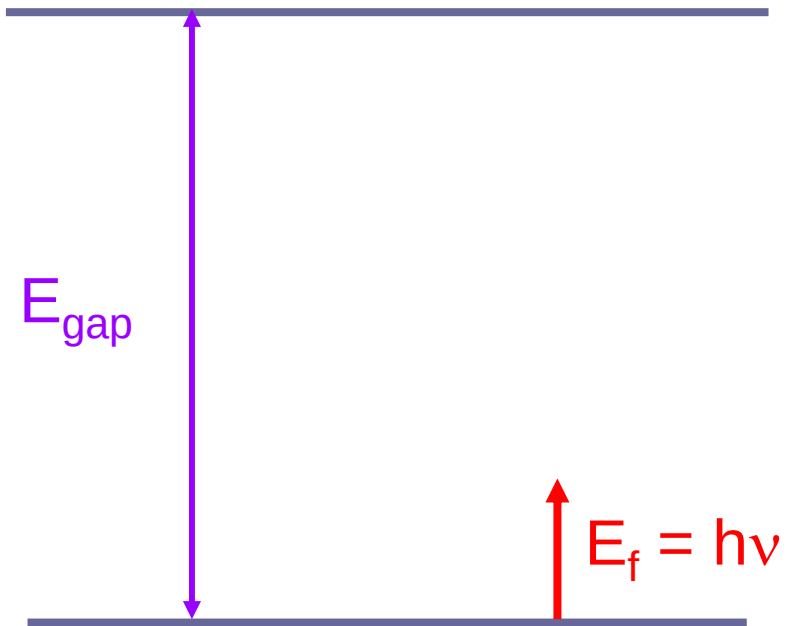
photon energy < bandgap



nonlinear interaction

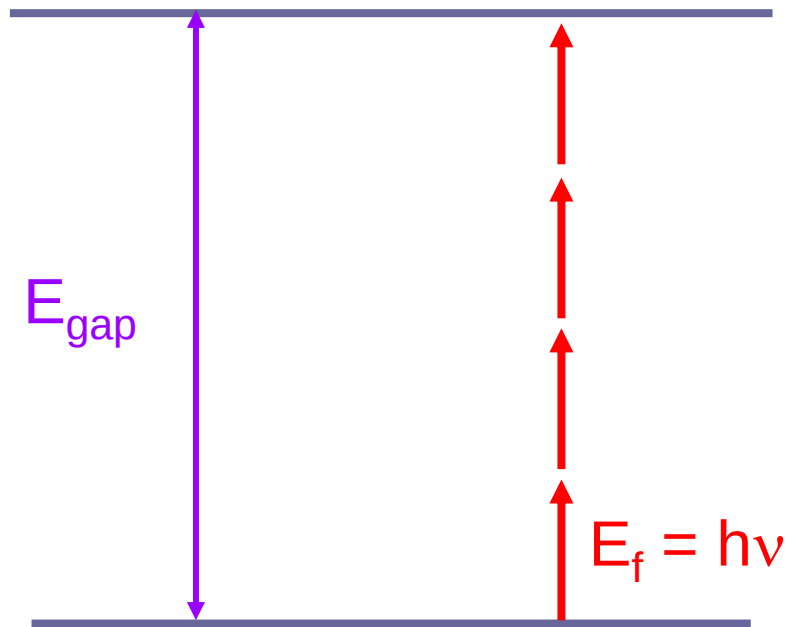
fs-micromachining

nonlinear interaction



fs-micromachining

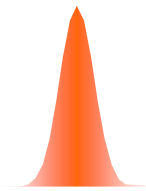
nonlinear interaction



multiphoton absorption

introduction

Ti:Sapphire lasers



100 fs



50 fs



20 fs

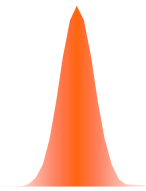
Very intense light

Laser intensities ~ 100 GW/cm²
1 x 10¹¹W/cm²

Laser pointer: 1 mW/cm² (1 x 10⁻³ W/ cm²)

introduction

Ti:Sapphire lasers



100 fs



50 fs



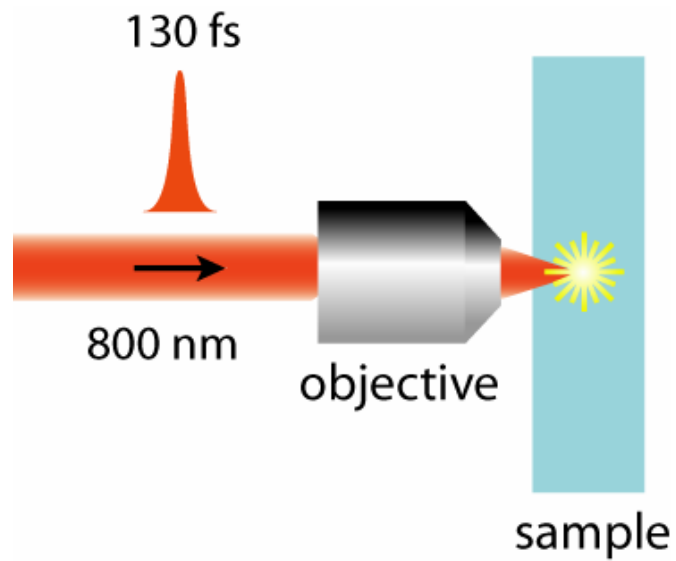
20 fs

Very intense light

Nonlinear Optical Phenomena

fs-laser microfabrication

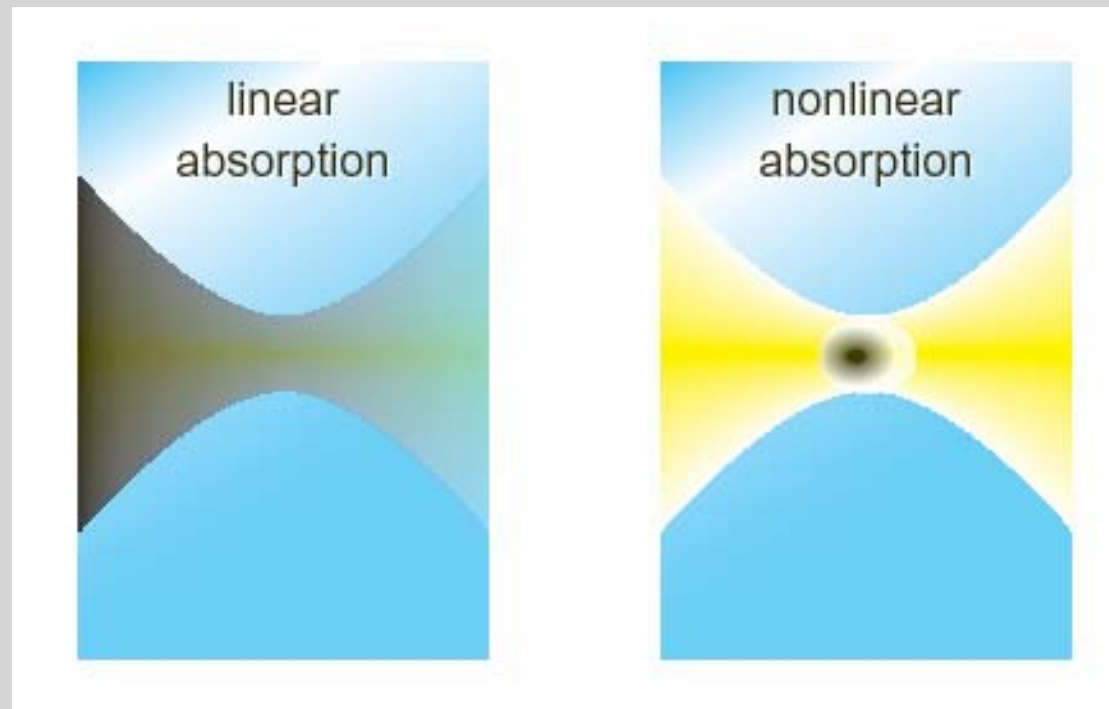
focus laser beam inside material



Two-photon absorption

Nonlinear interaction provides spatial confinement of the excitation

fs-microfabrication

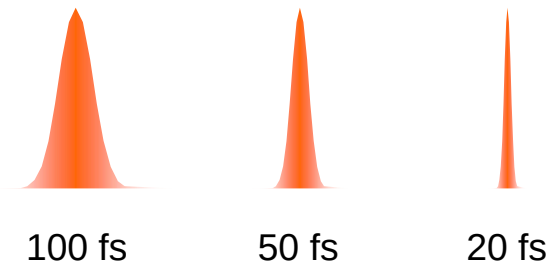


$$\alpha = \alpha_0$$

$$\alpha = \alpha_0 + \beta I$$

femtosecond pulses

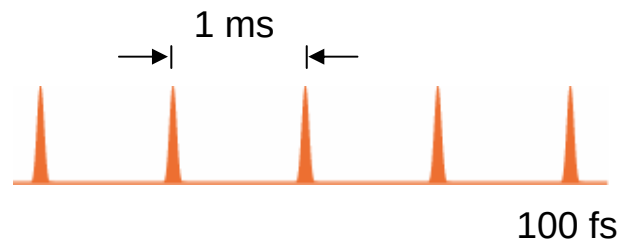
Ti:Sapphire lasers



$1 \text{ fs} = 10^{-15} \text{ s}$

Repetition rate

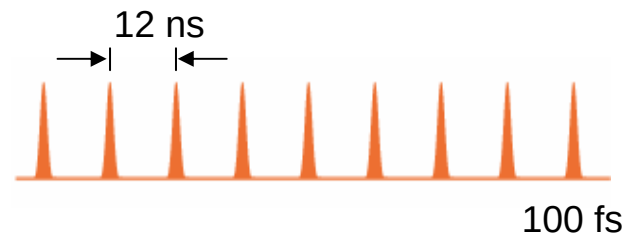
1 KHz



Energy

mJ

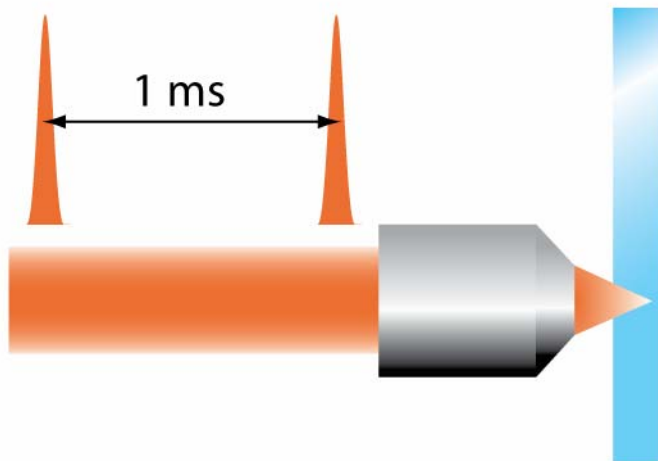
86 MHz



nJ

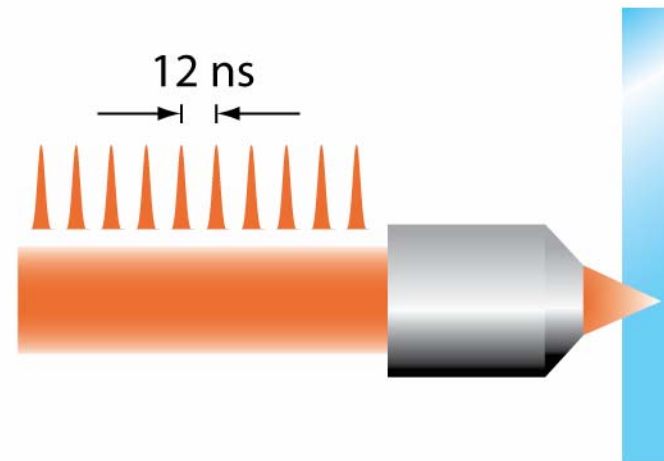
femtosecond pulses

amplified laser



repetitive

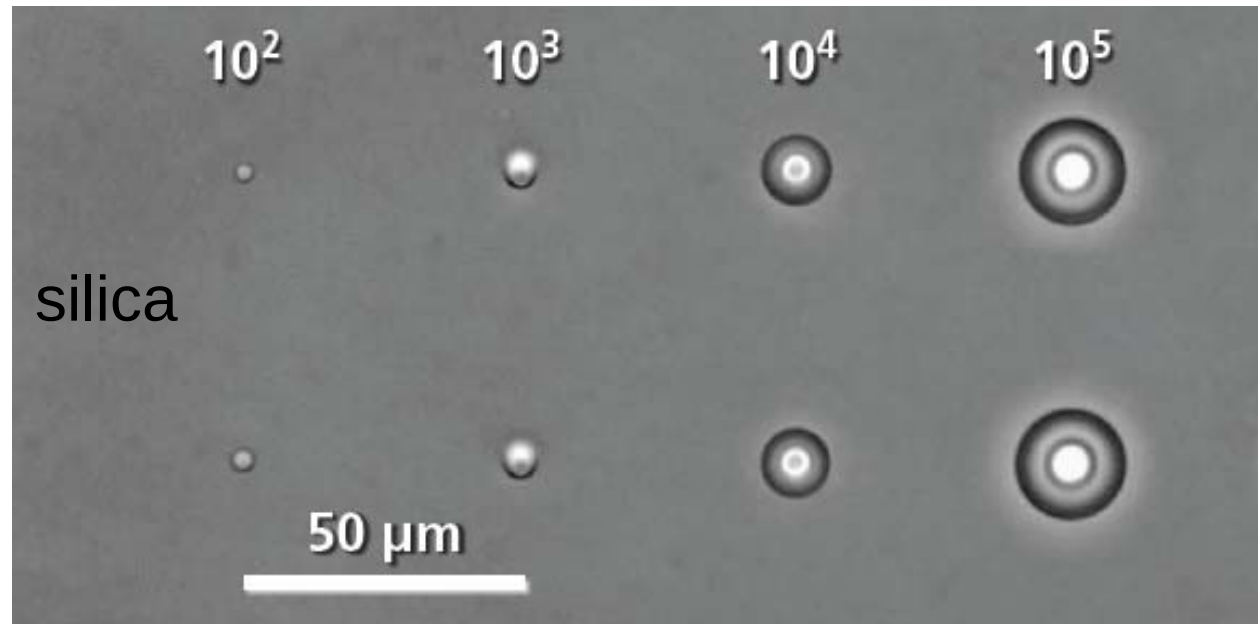
oscillator



cumulative

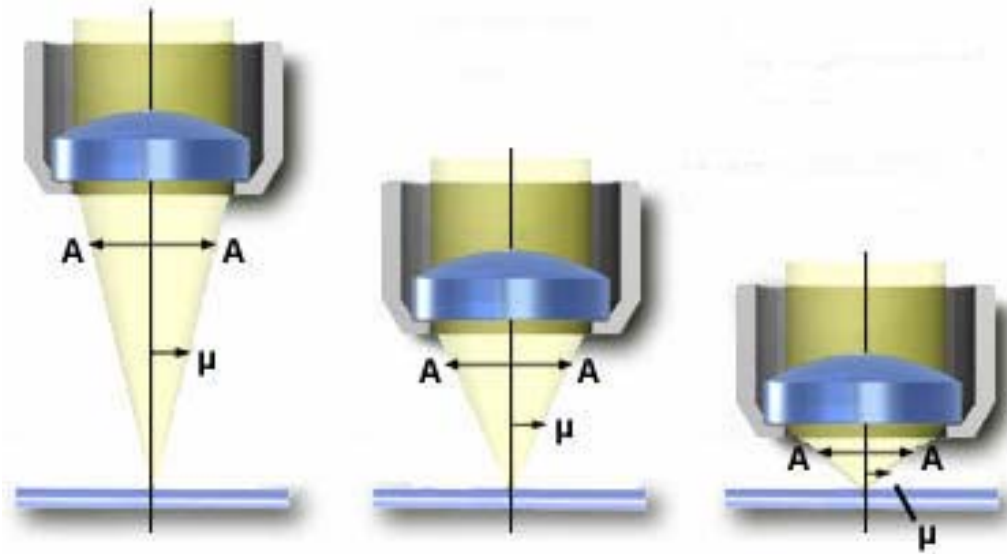
fs-micromachining

the longer the irradiation the longer the radius



E. Mazur – Harvard University

fs-micromachining: focusing



$$NA = 0.12$$

$$\mu = 7^\circ$$

$$NA = 0.34$$

$$\mu = 20^\circ$$

$$NA = 0.87$$

$$\mu = 60^\circ$$

what is the difference ?

high NA

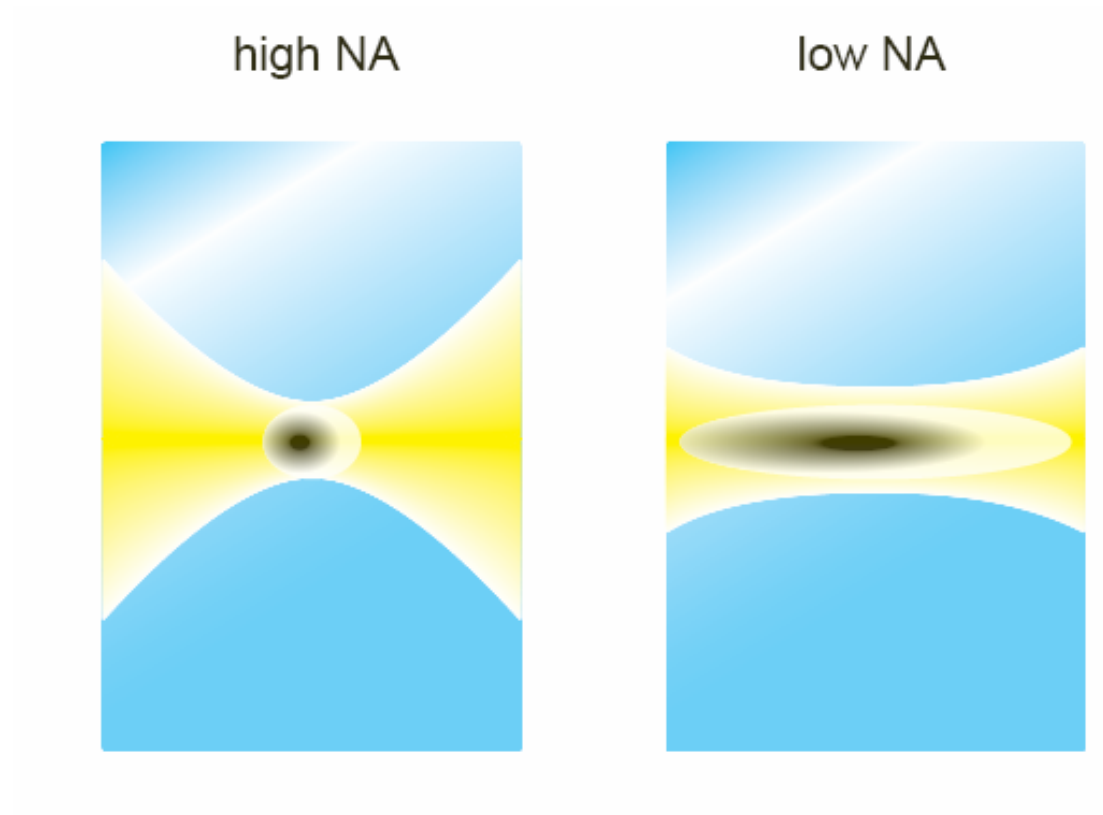


low NA



$$w_0 = \frac{\lambda}{\pi NA} \sqrt{1 - NA^2}$$

very different confocal length/interaction length



fs-micromachining

microfabrication can be controlled by

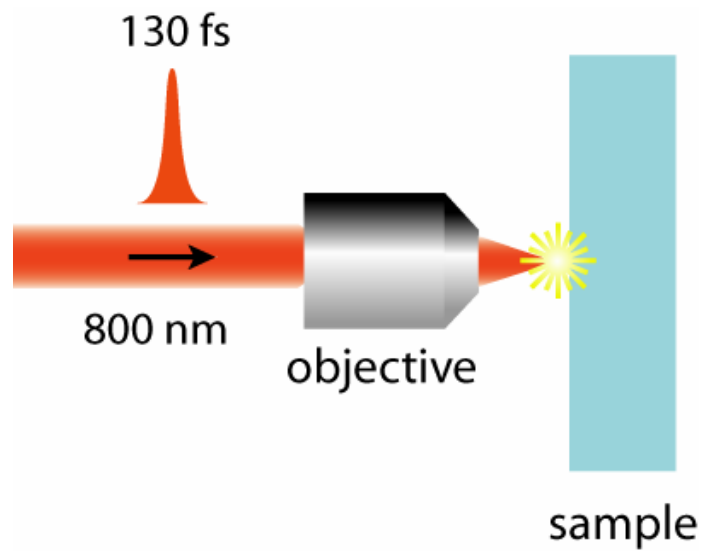
- objective NA
- number of pulses – scanning speed
- pulse energy

two main techniques

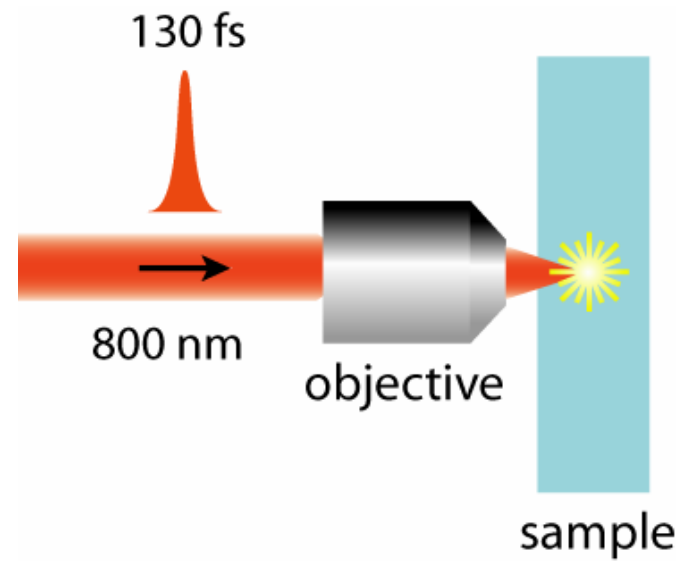
- fs-laser micromachining
- microfabrication via two-photon polymerization

fs-laser micromachining

Surface

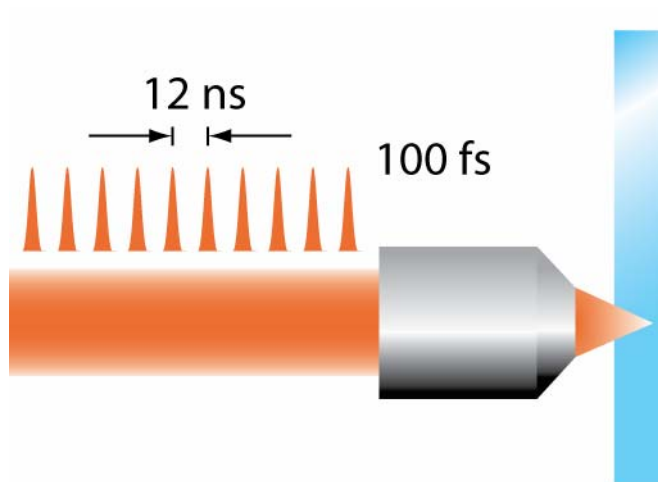


Volume



fs-pulses for micromachining polymers

Oscillator: 80 MHz, 5 nJ

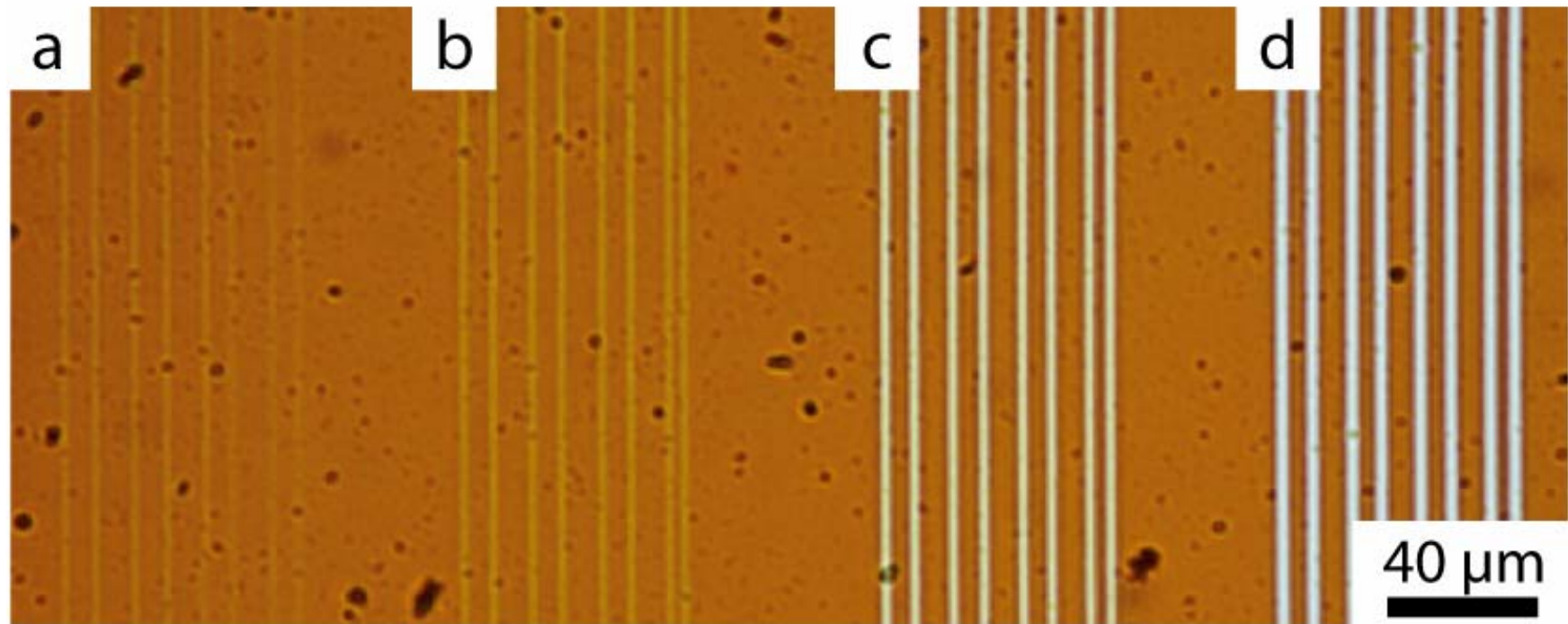


heat diffusion time: $t_{\text{diff}} \sim 1 \mu\text{s}$

cumulative

Micromachining the conductive polymer MEH-PPV

optical microscopy



a: 0.07 nJ

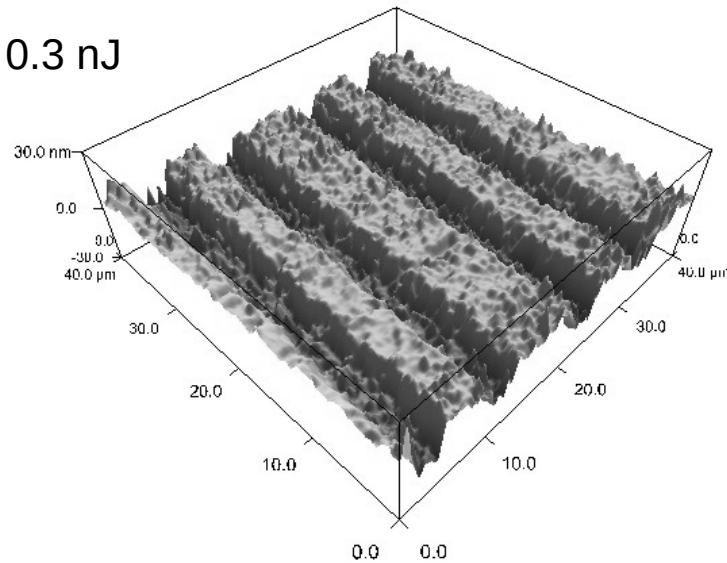
b: 0.14 nJ

c: 0.34 nJ

d: 0.68 nJ

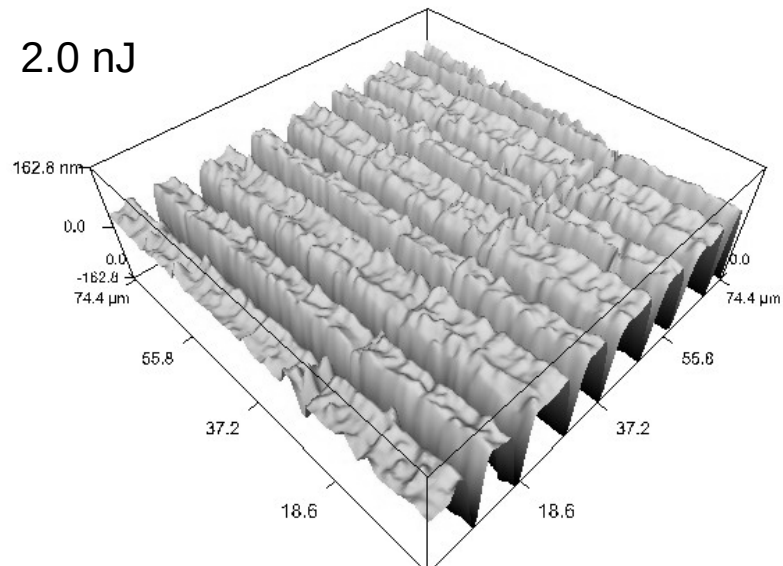
Micromachining the conductive polymer MEH-PPV

a 0.3 nJ

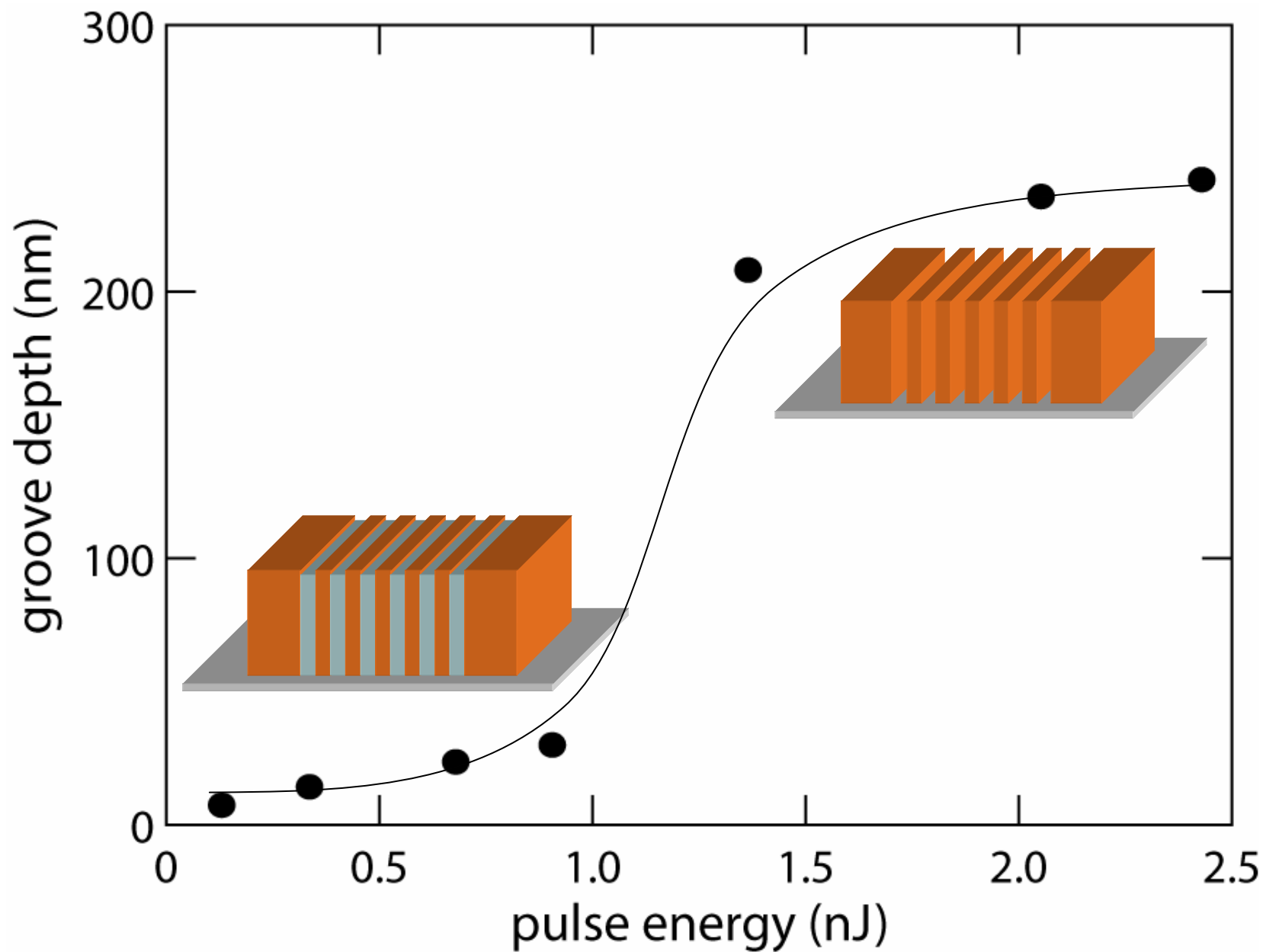


atomic force microscopy

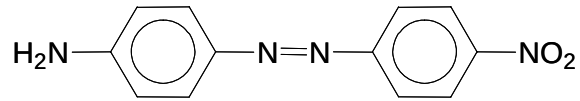
b 2.0 nJ



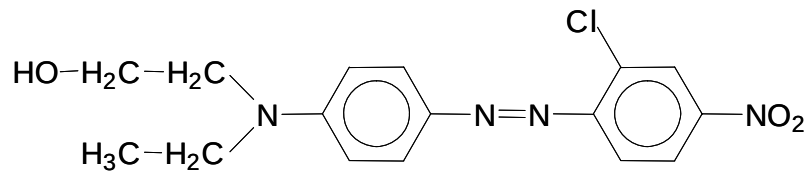
Micromachining the conductive polymer MEH-PPV



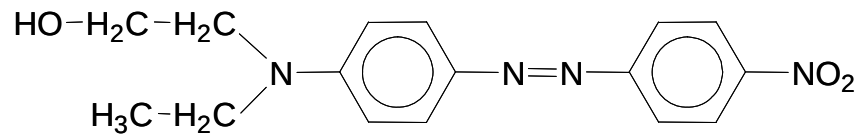
Waveguides in azo-polymers



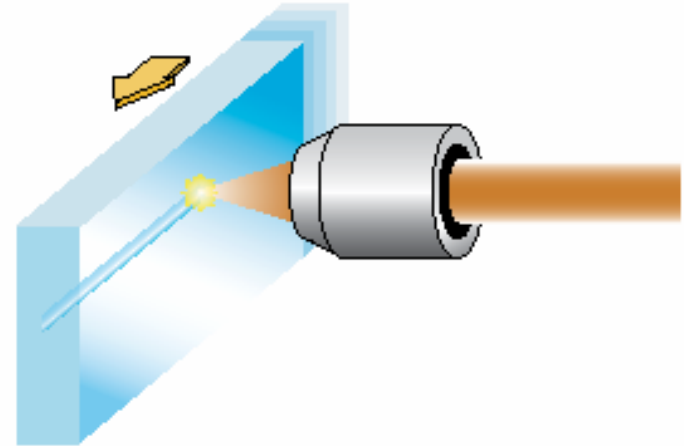
DO3



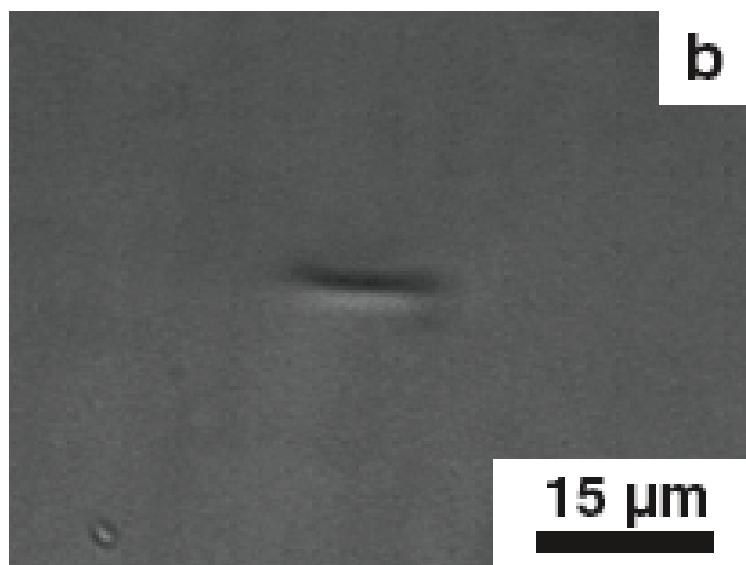
DR13



DR1

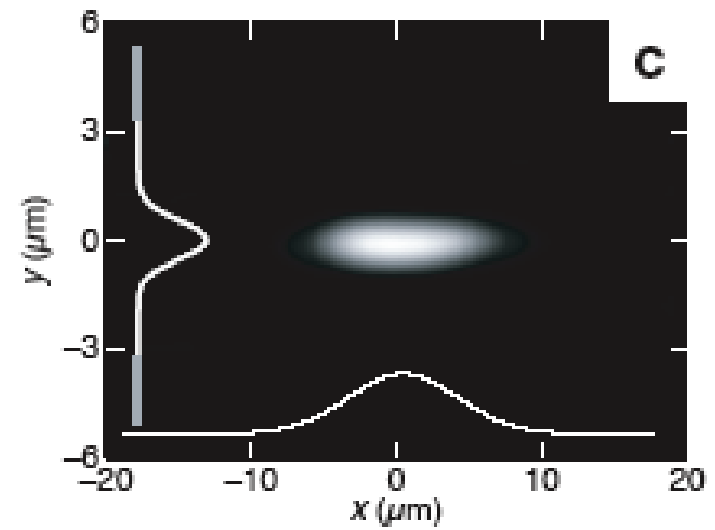
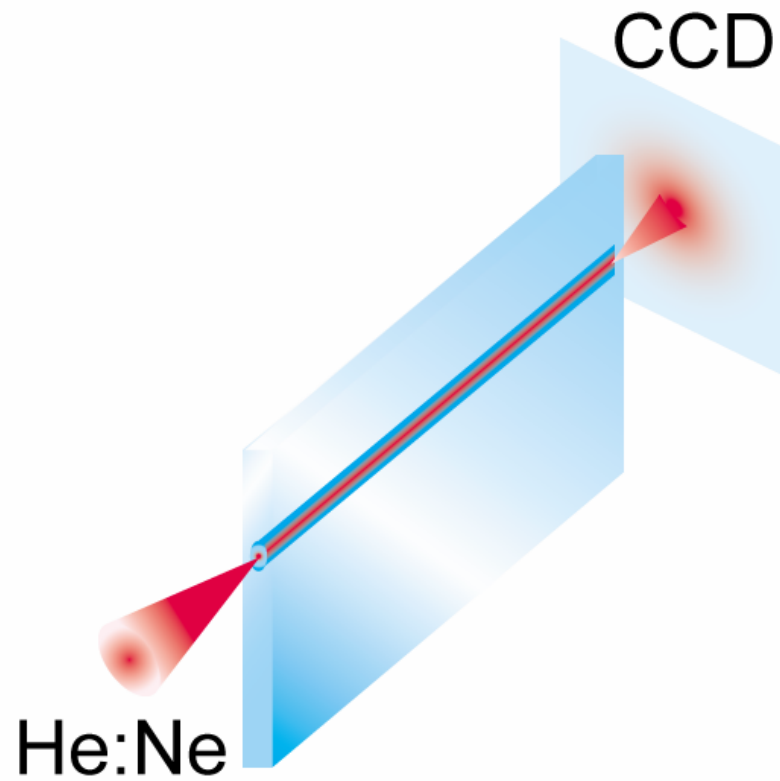


Waveguides in azo-polymers



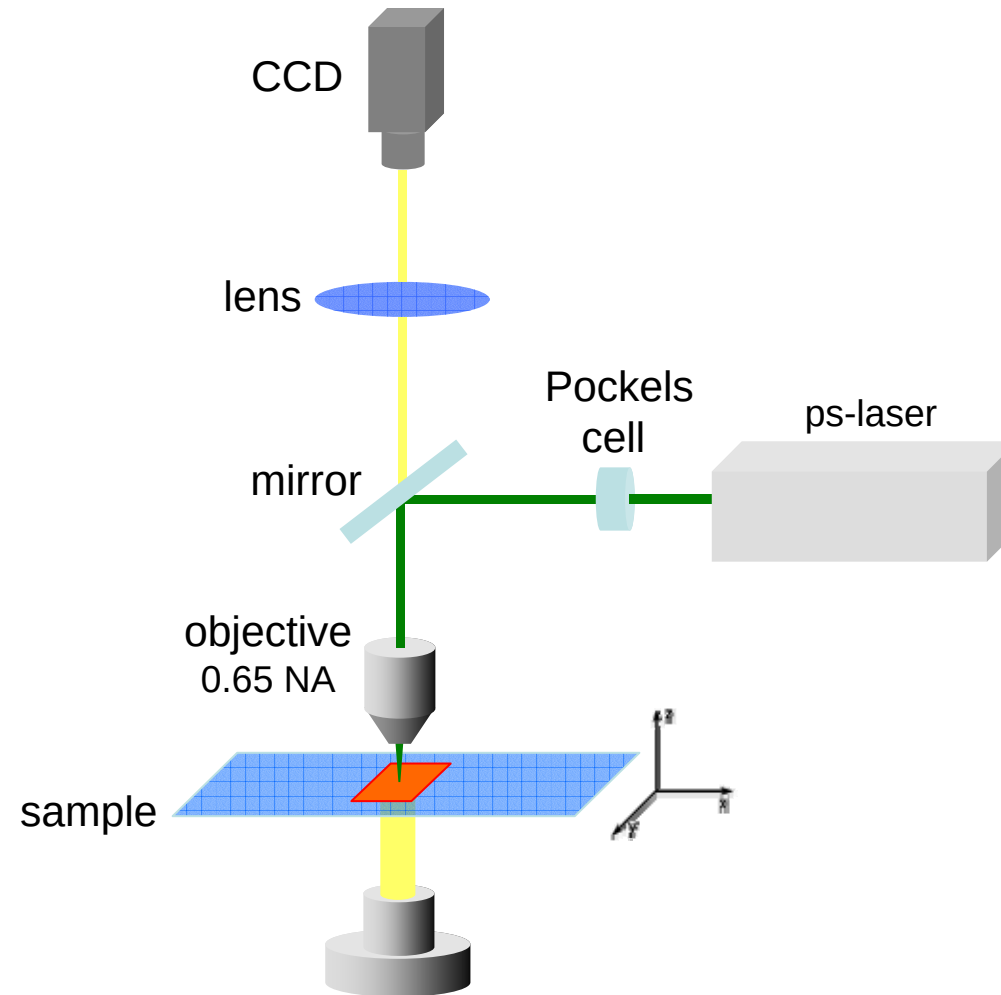
- (a) Optical microscope image of the waveguides micromachined (PMMA/DR1)
- (b) Cross-sectional view of the waveguides

waveguides in azo-polymers

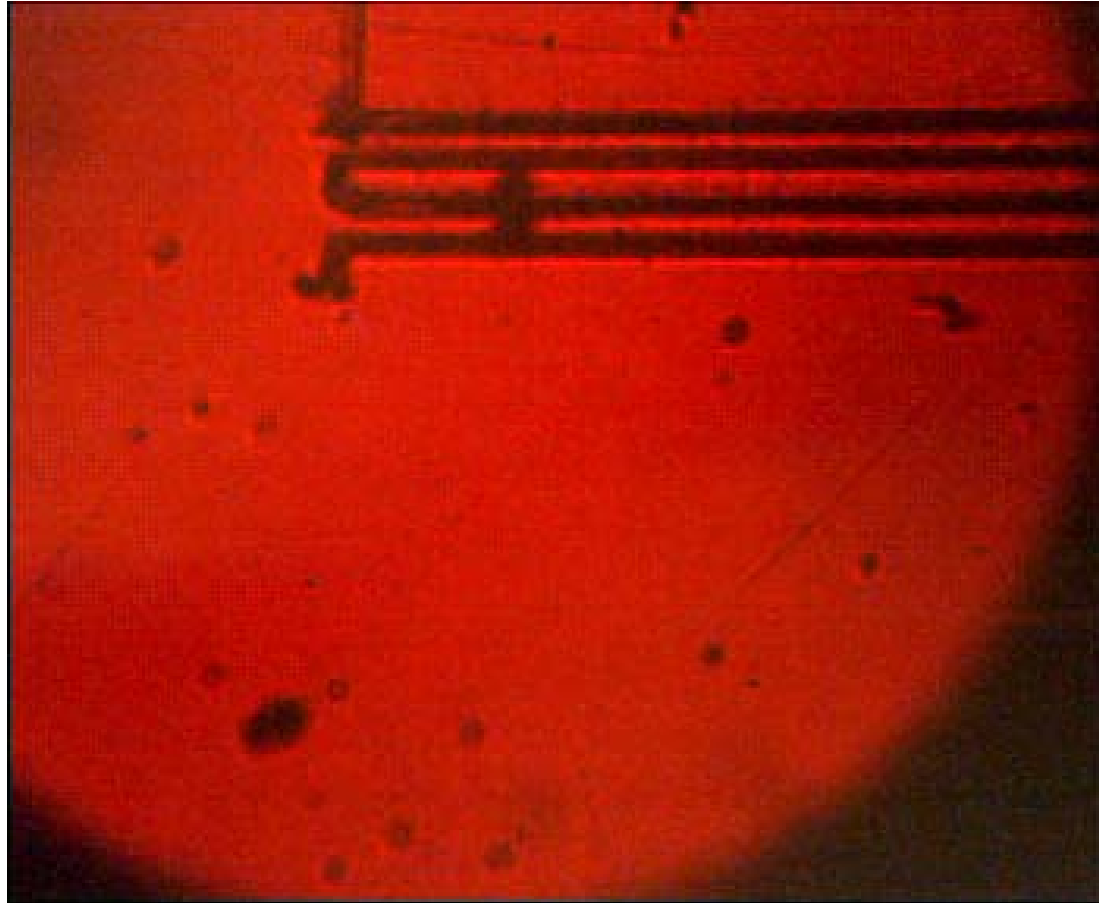


(c) Output image of the mode profile of 632.8-nm light coupled through the waveguide

microstructuring polymer: super hydrophobic surface

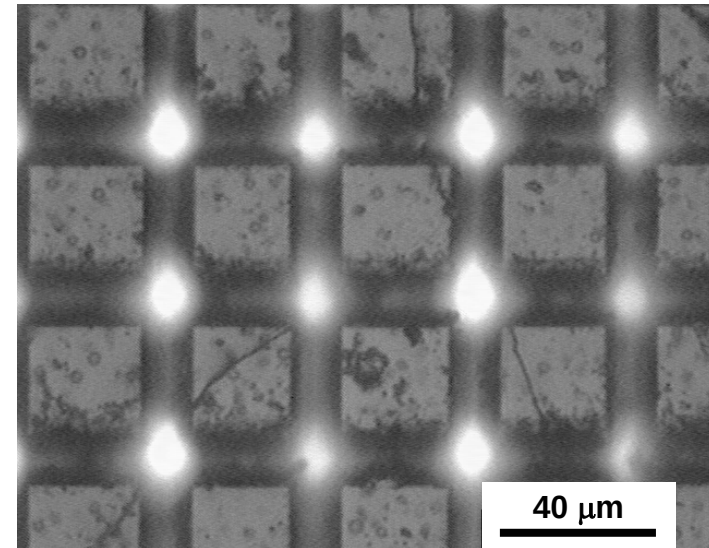
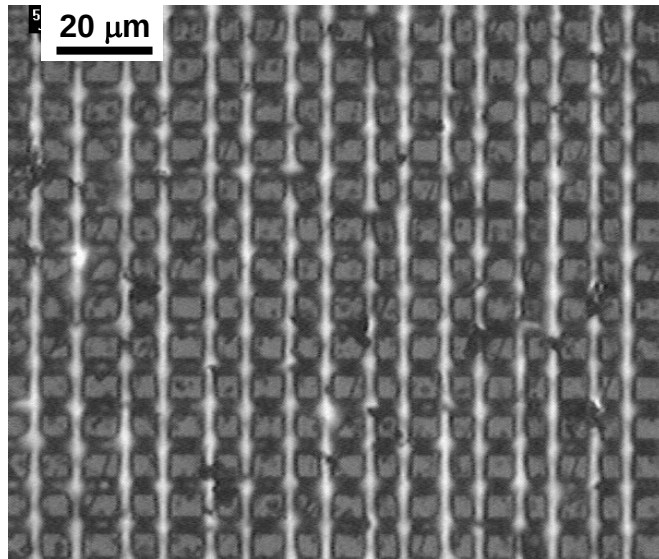


microstructuring polymer: super hydrophobic surface



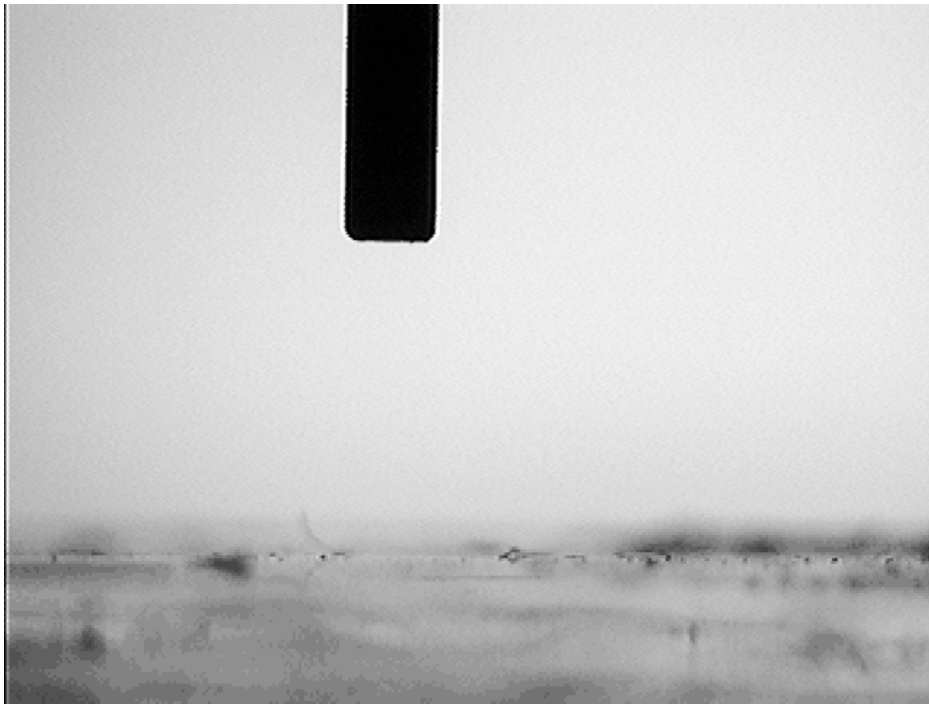
laser microfabrication: super hydrophobic surface

examples of fabricated surfaces

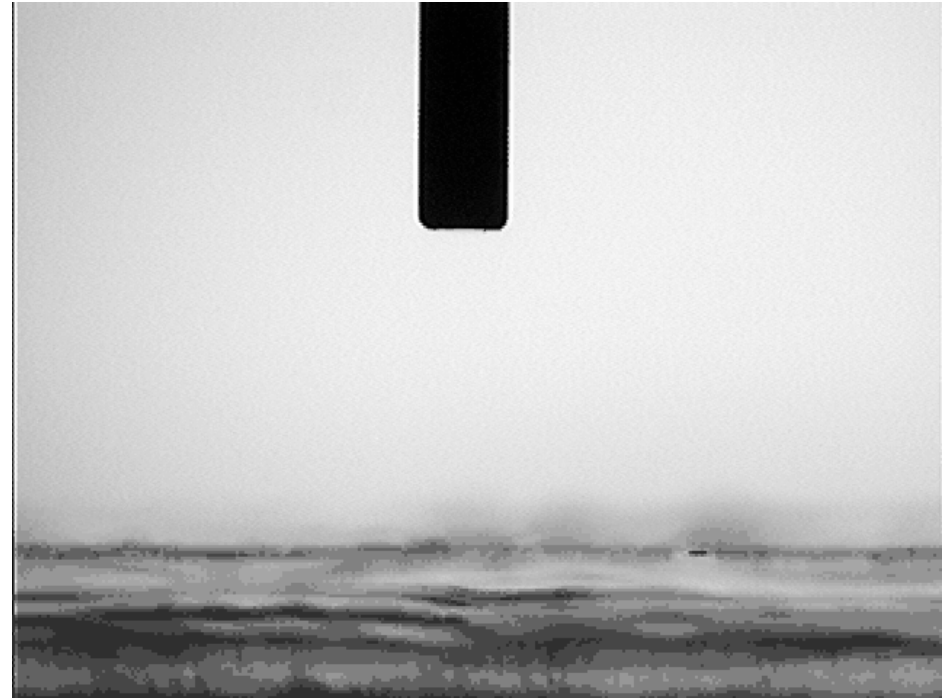


laser microfabrication: super hydrophobic surface

Superhydrophobic surfaces

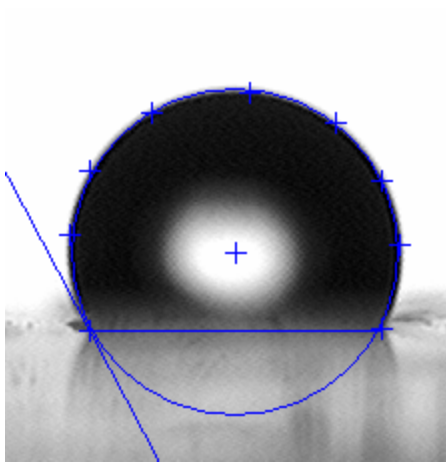


flat surface



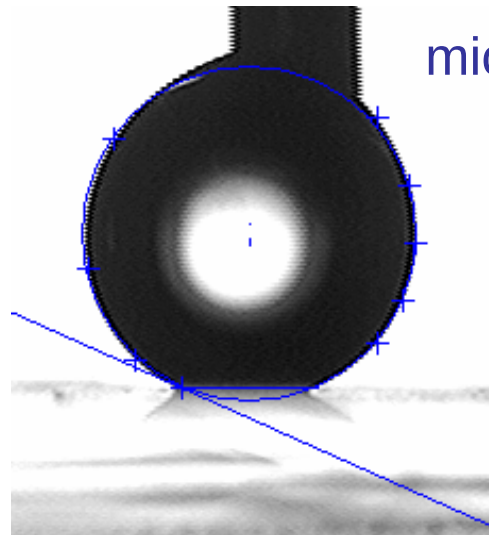
microstructured surface

microstructuring polymer



flat surface

$$\theta = 118^\circ$$



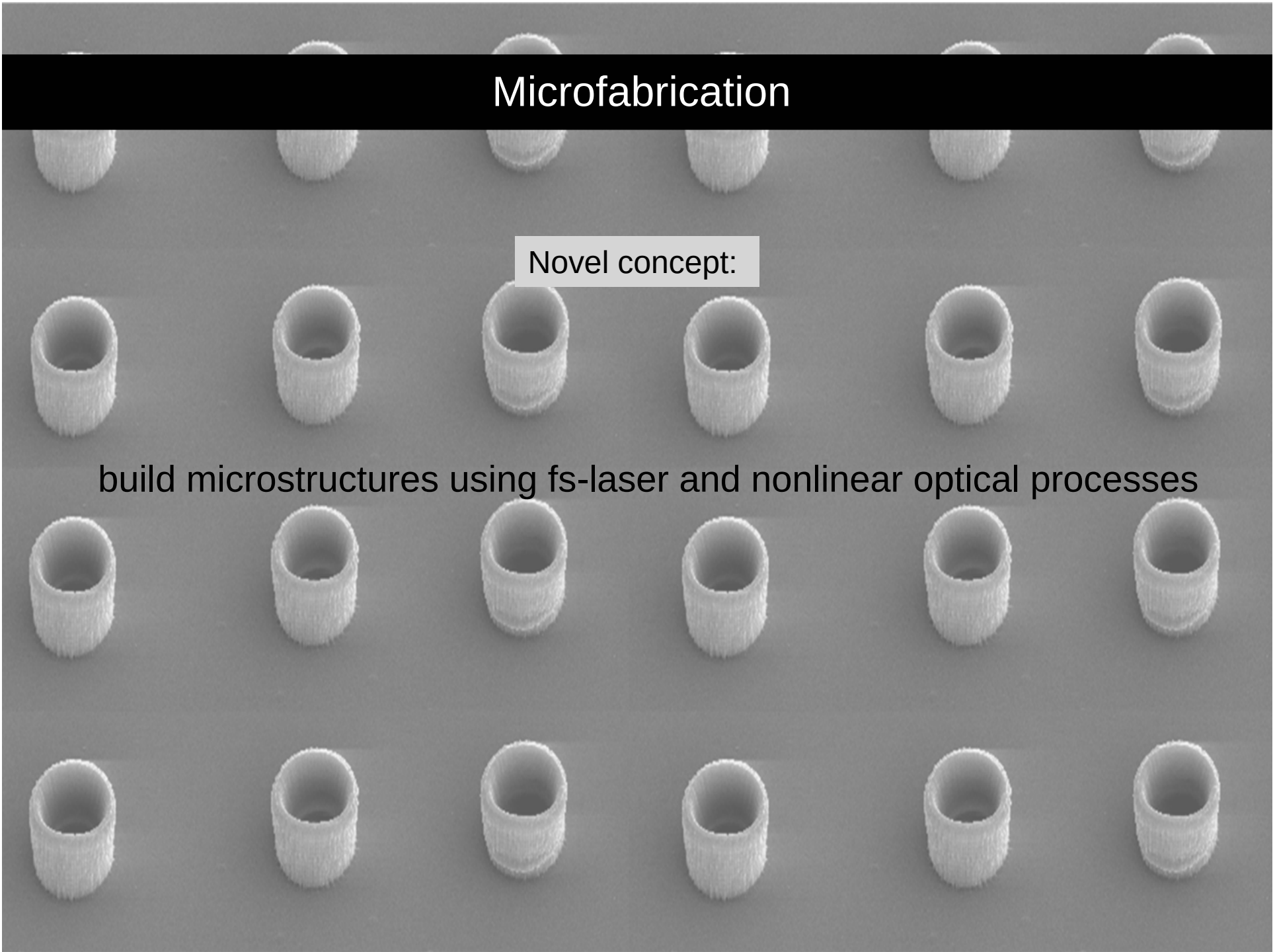
microstructured surface

$$\theta = 160^\circ$$

Microfabrication

Novel concept:

build microstructures using fs-laser and nonlinear optical processes



two-photon polymerization

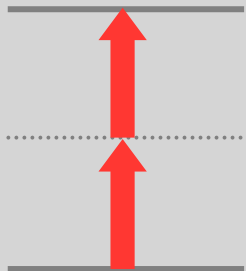
applications

- micromechanics
- waveguides
- microfluidics
- biology
- optical devices

Two-photon polymerization

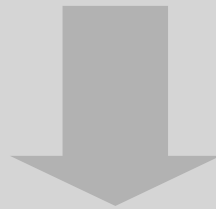


Photoinitiator is excited by ***two-photon absorption***



$$R_{2PA} \propto I^2$$

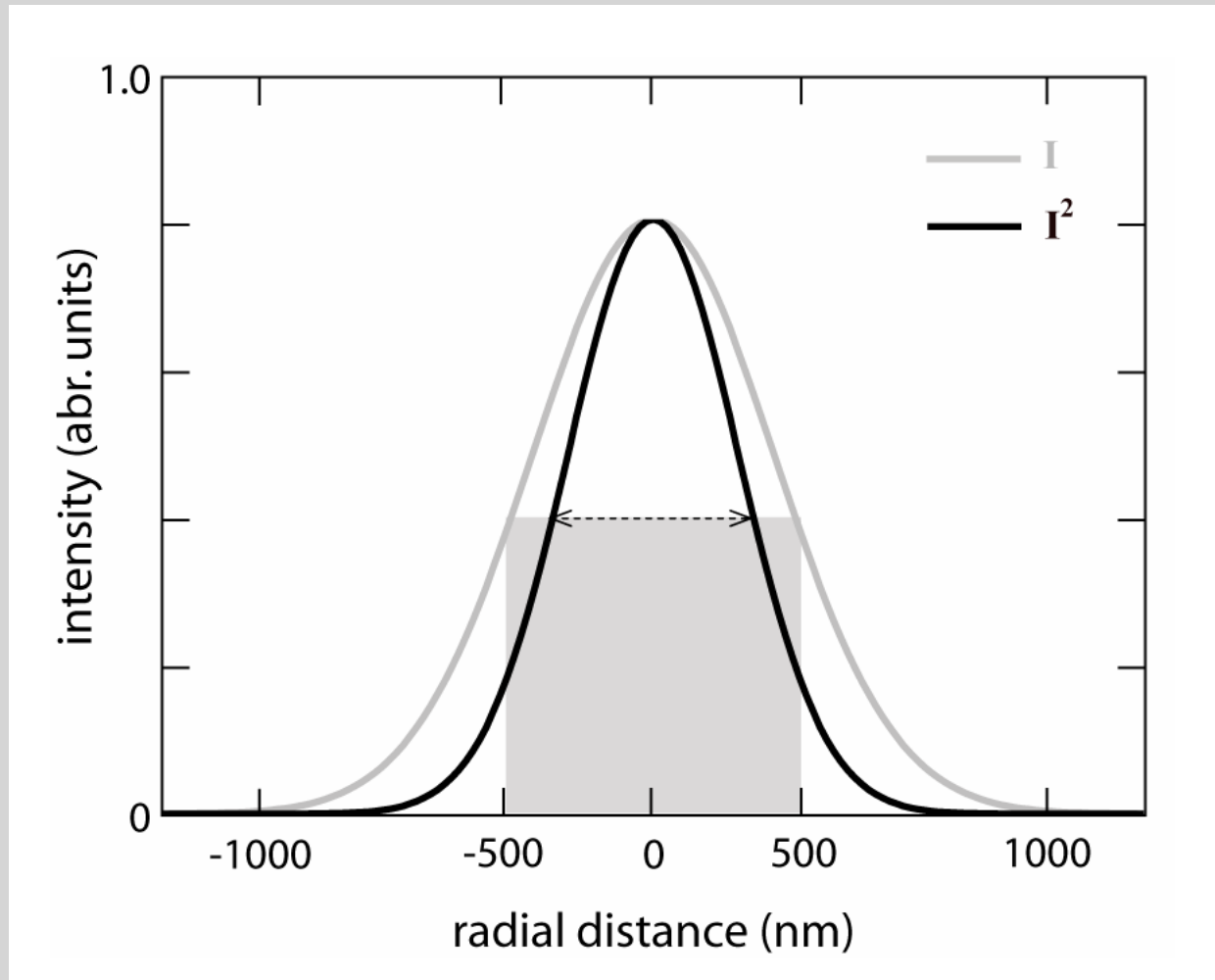
The polymerization is confined to the focal volume.



High spatial resolution

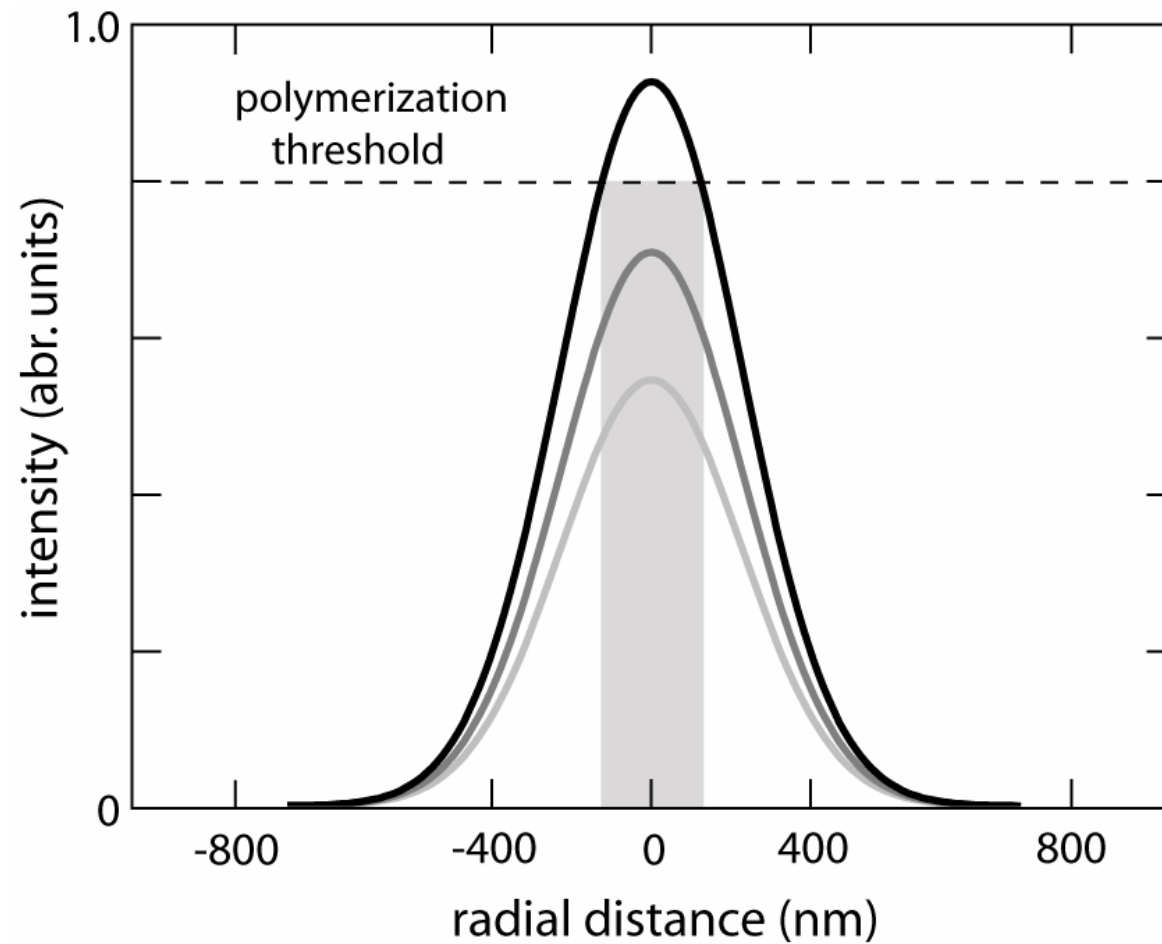


Two-photon polymerization



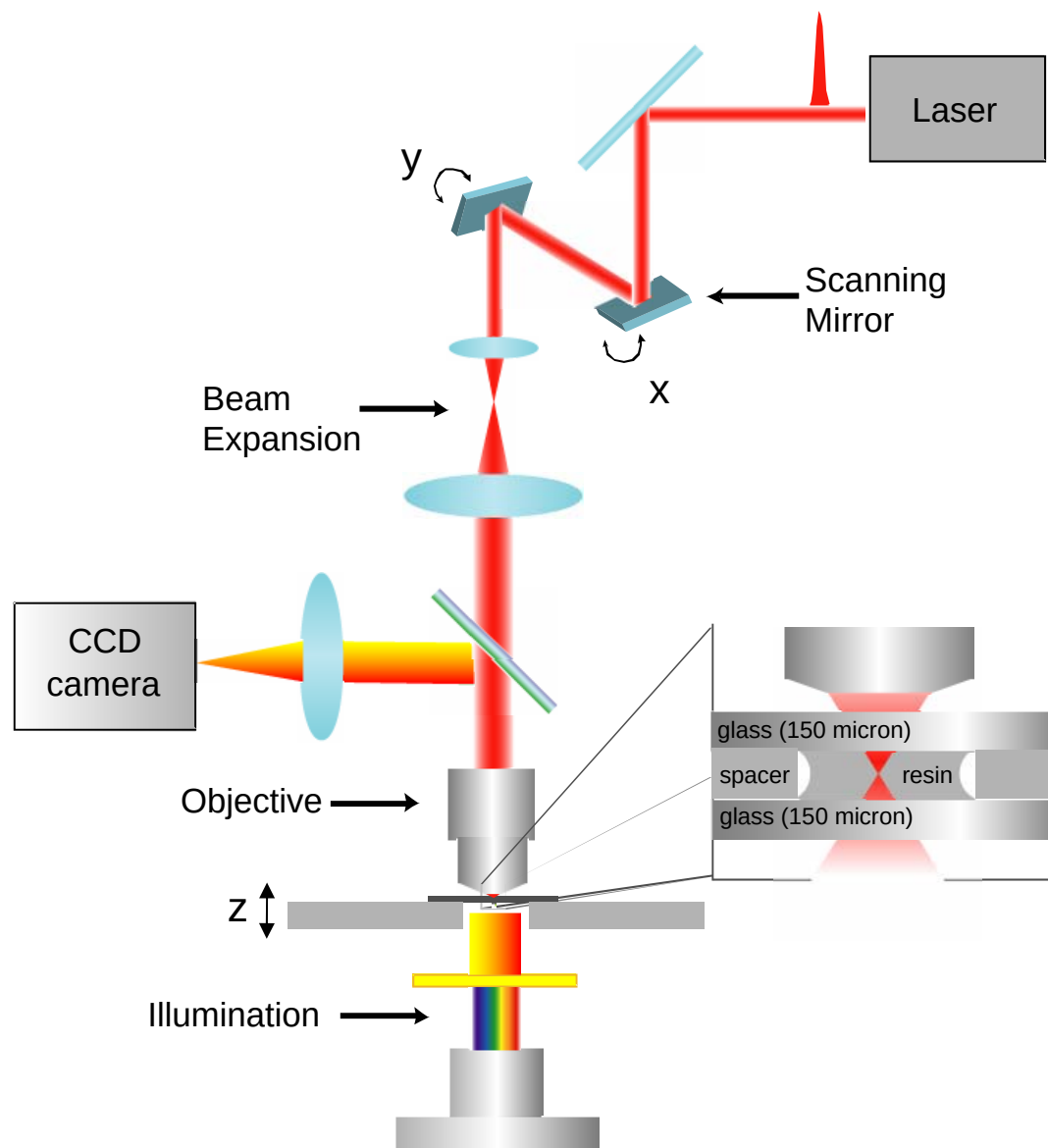
bellow the diffraction limit

Two-photon polymerization



even higher spatial resolution

Two-photon polymerization setup



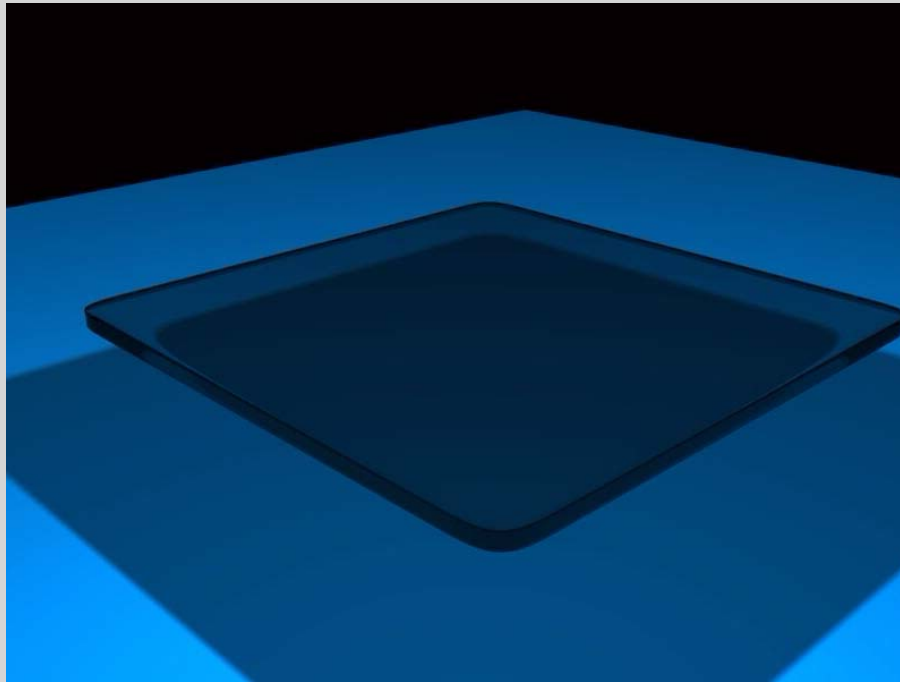
Ti:sapphire laser oscillator

- 130 fs
- 800 nm
- 76 MHz
- 20 mW

Objective

40 x
0.65 NA

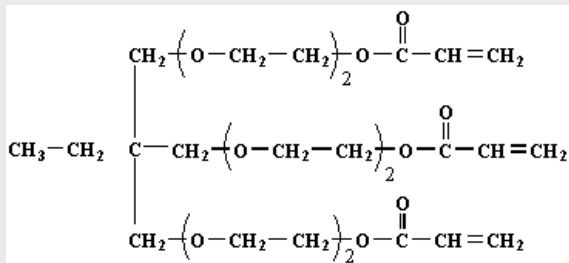
Two-photon polymerization



Resin preparation

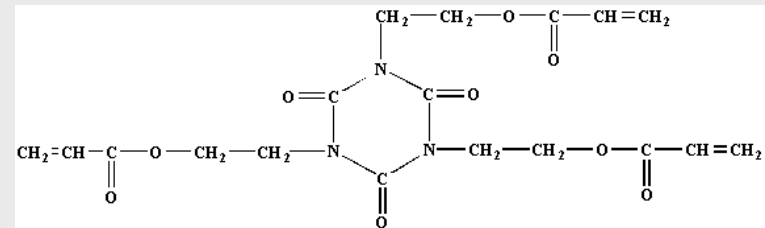
Monomers

Monomer A



reduces the shrinkage upon polymerization

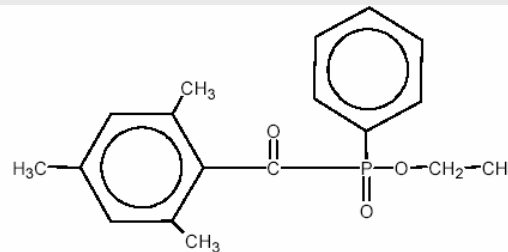
Monomer B



gives hardness to the polymeric structure

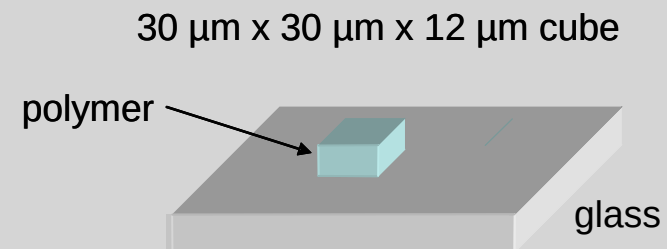
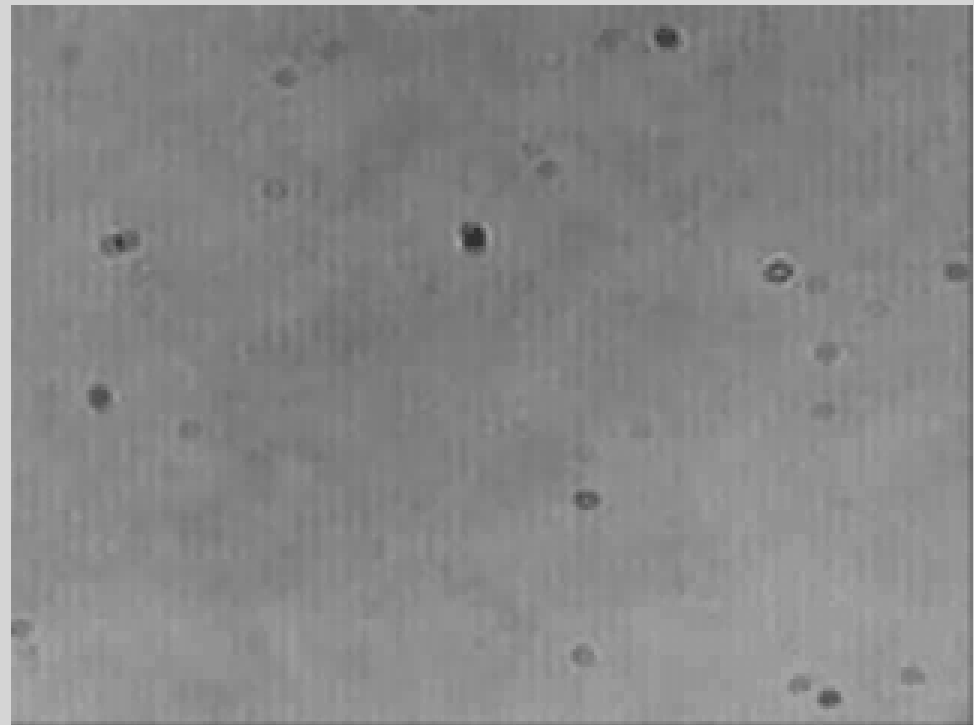
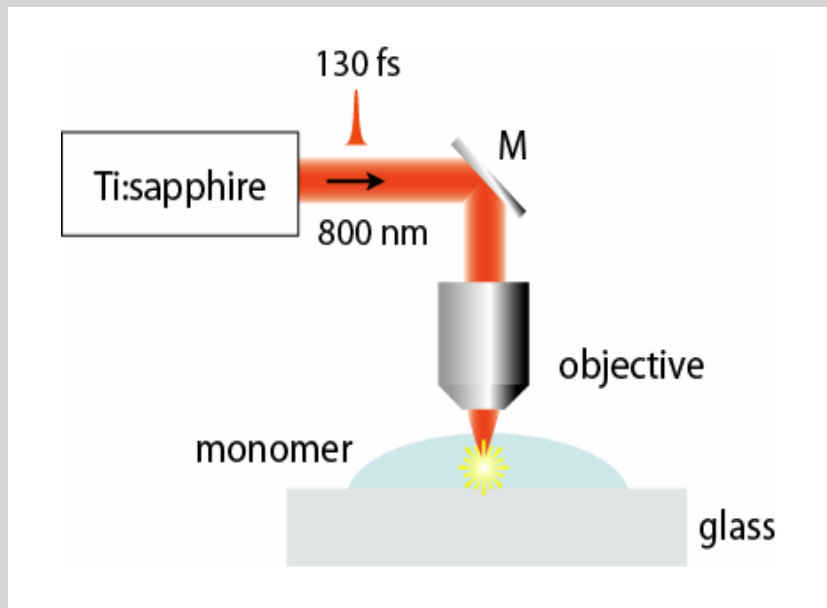
Photoinitiator

Lucirin TPO-L

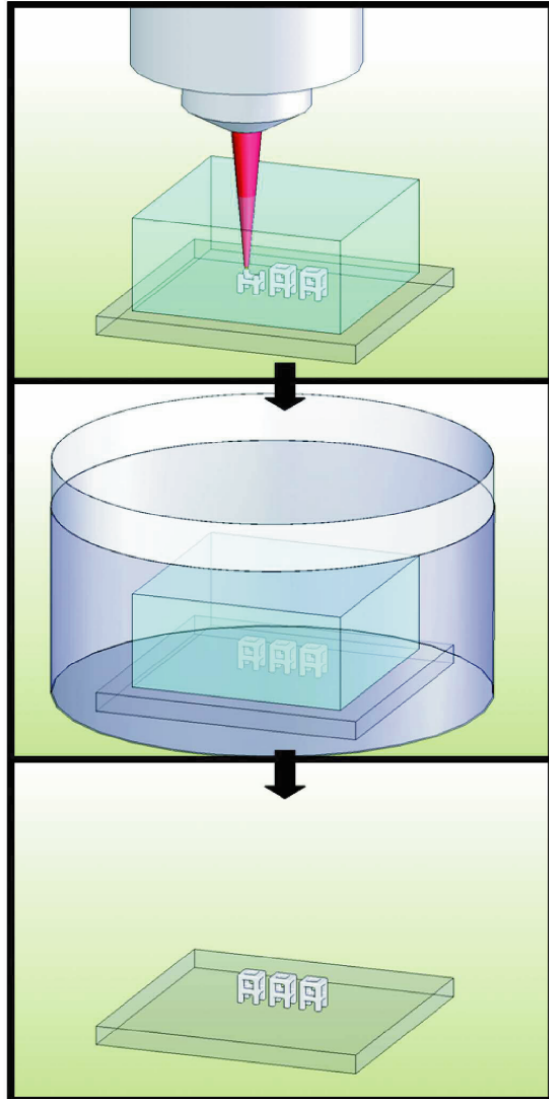


Appl. Phys. A, 90, 633–636 (2008)

Two-photon polymerization



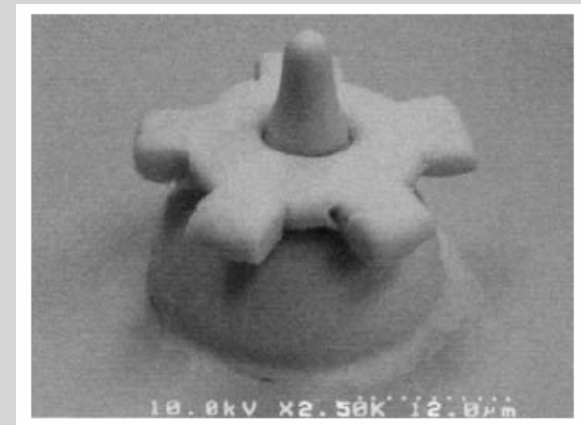
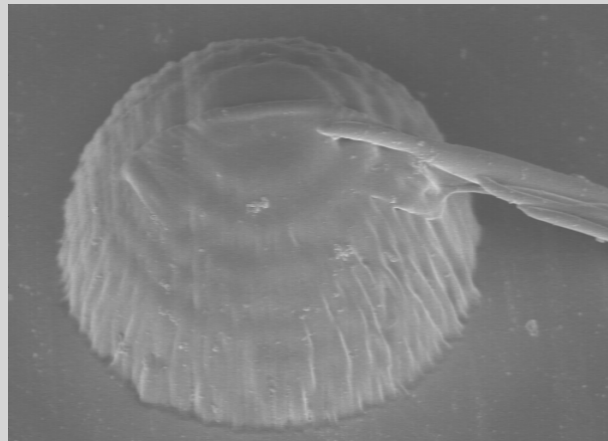
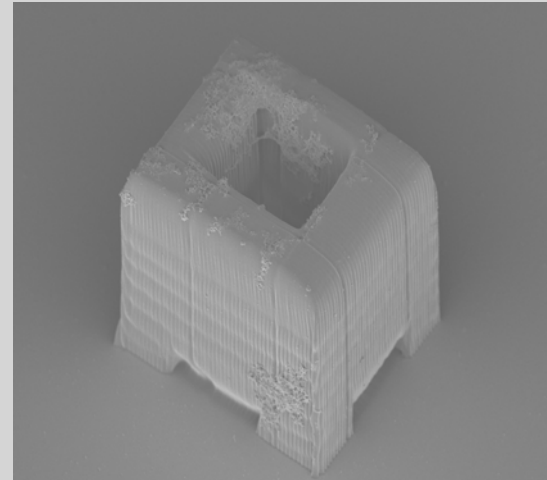
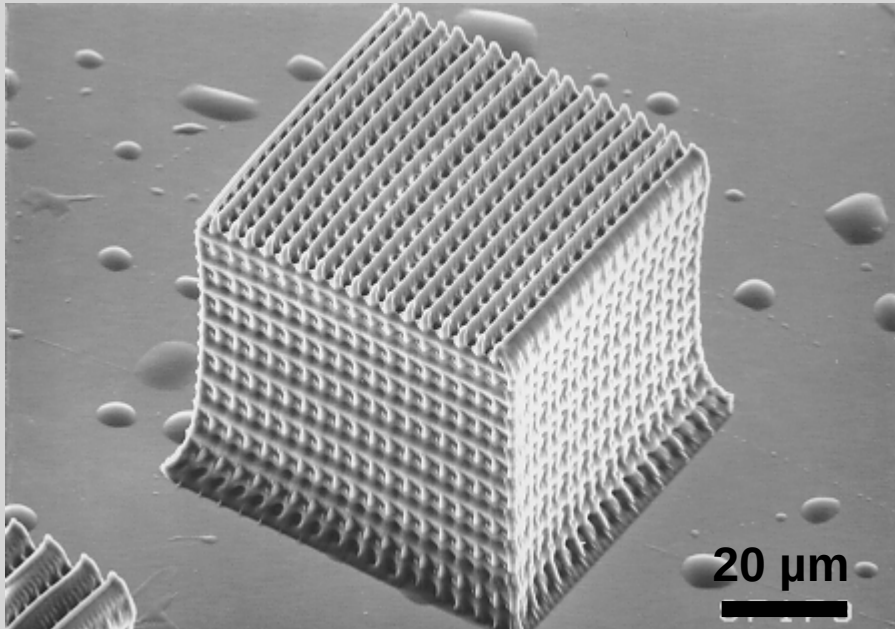
Two-photon polymerization



After the fabrication, the sample is immersed in ethanol to wash away any unsolidified resin and then dried

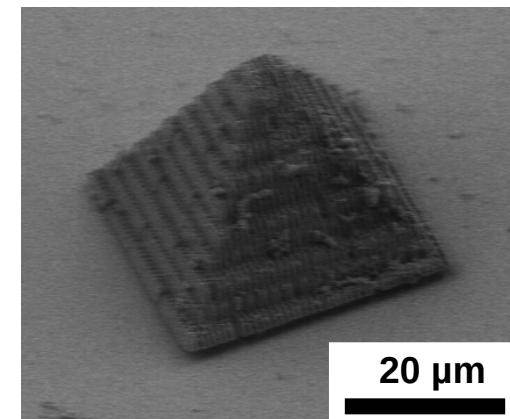
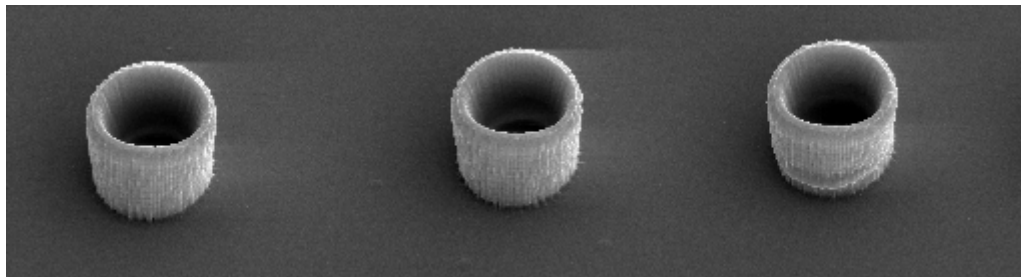
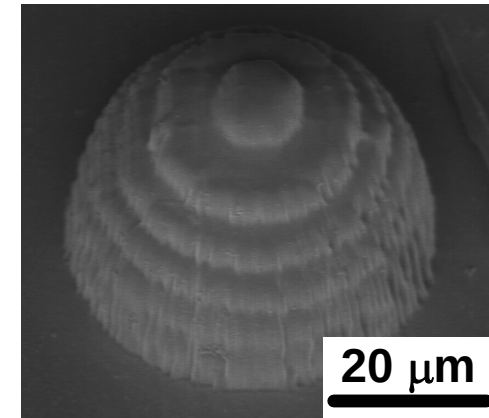
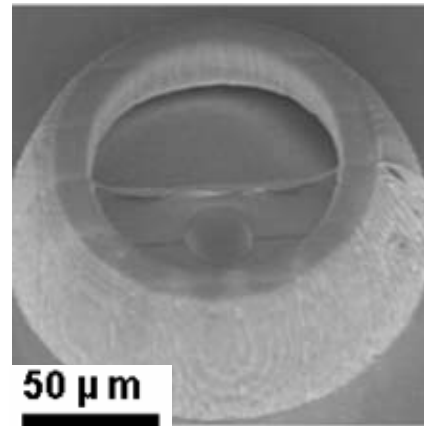
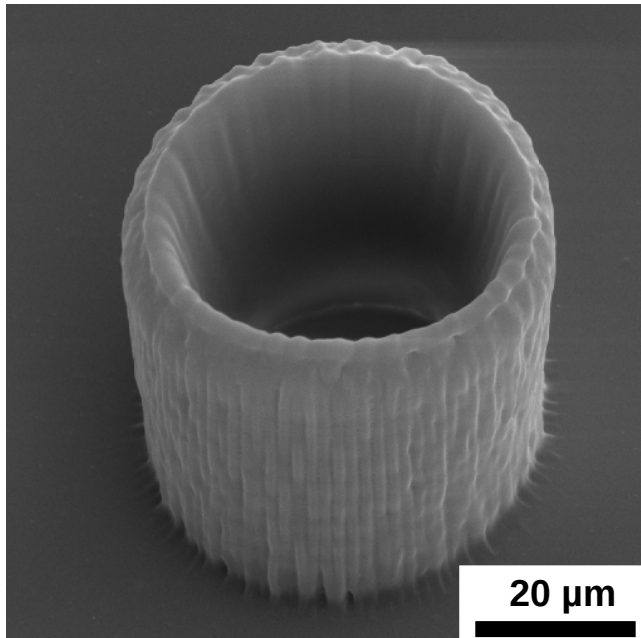
two-photon polymerization

photonic crystal – J. W. Perry

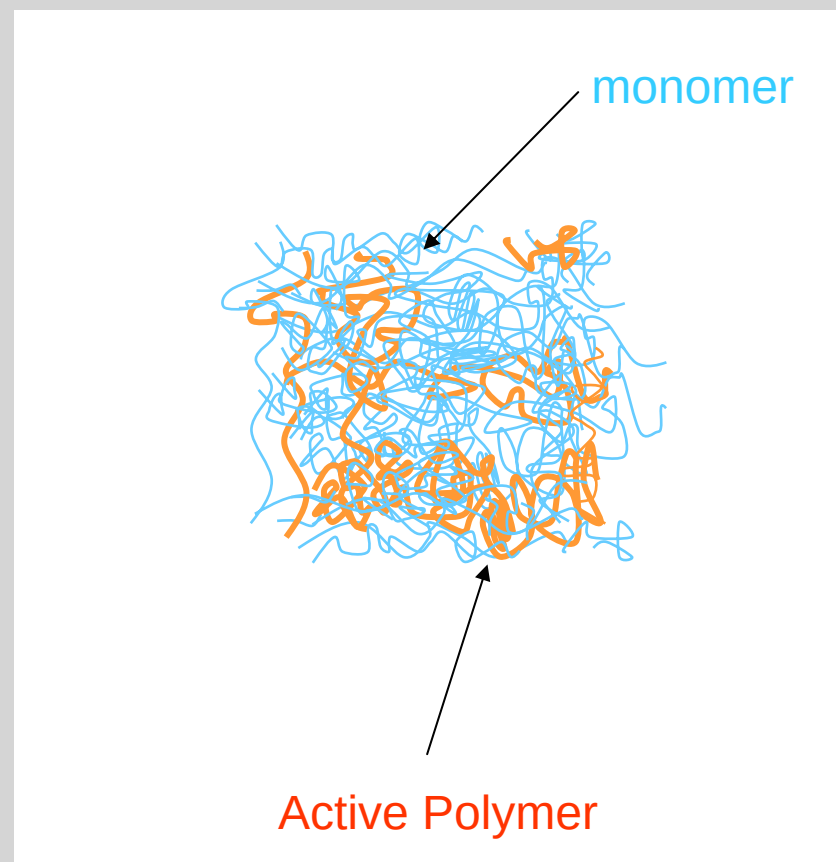
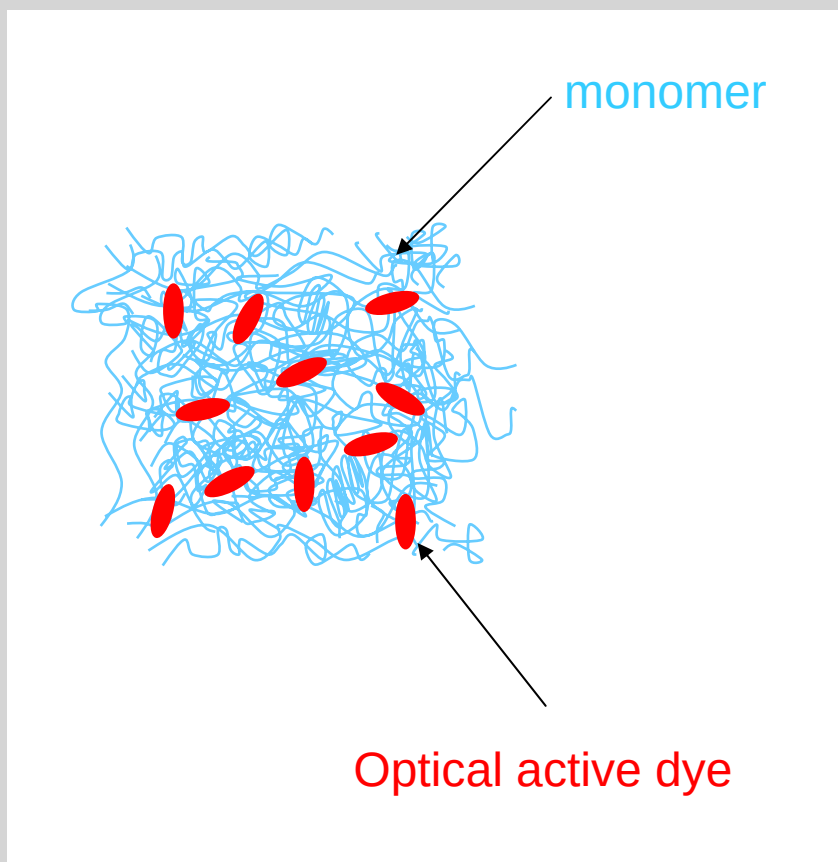


Two-photon polymerization

Microstructures fabricated by two-photon polymerization



Microstructures containing active compounds



Applications of two-photon polymerization

Optics and Photonics

Doping microstructures with organic molecules and metals

- fluorescence
- birefringence
- conductivity

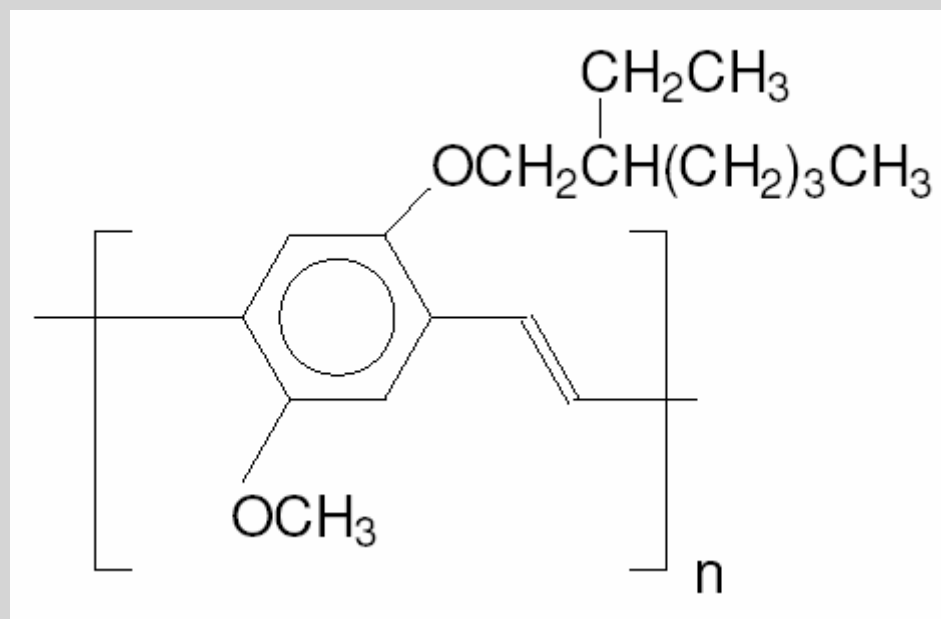
Bio-applications

Fabrication using bio-compatible resins to biological applications

- tissue engineering scaffolds
- fabrication of microneedle
- cell study

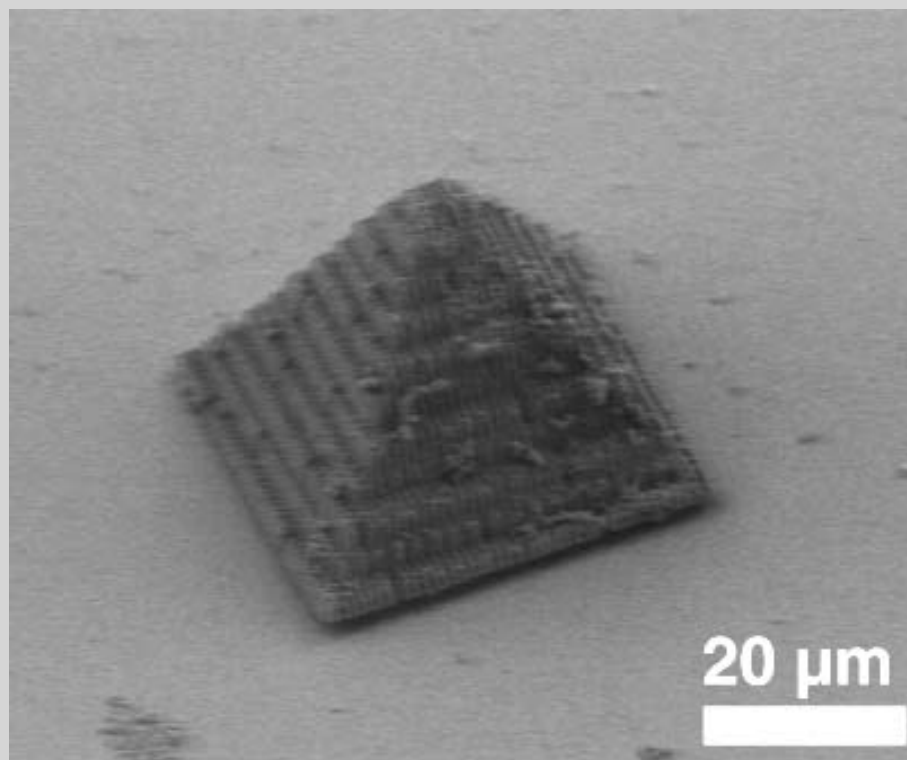
Microstructures containing MEH-PPV

MEH-PPV

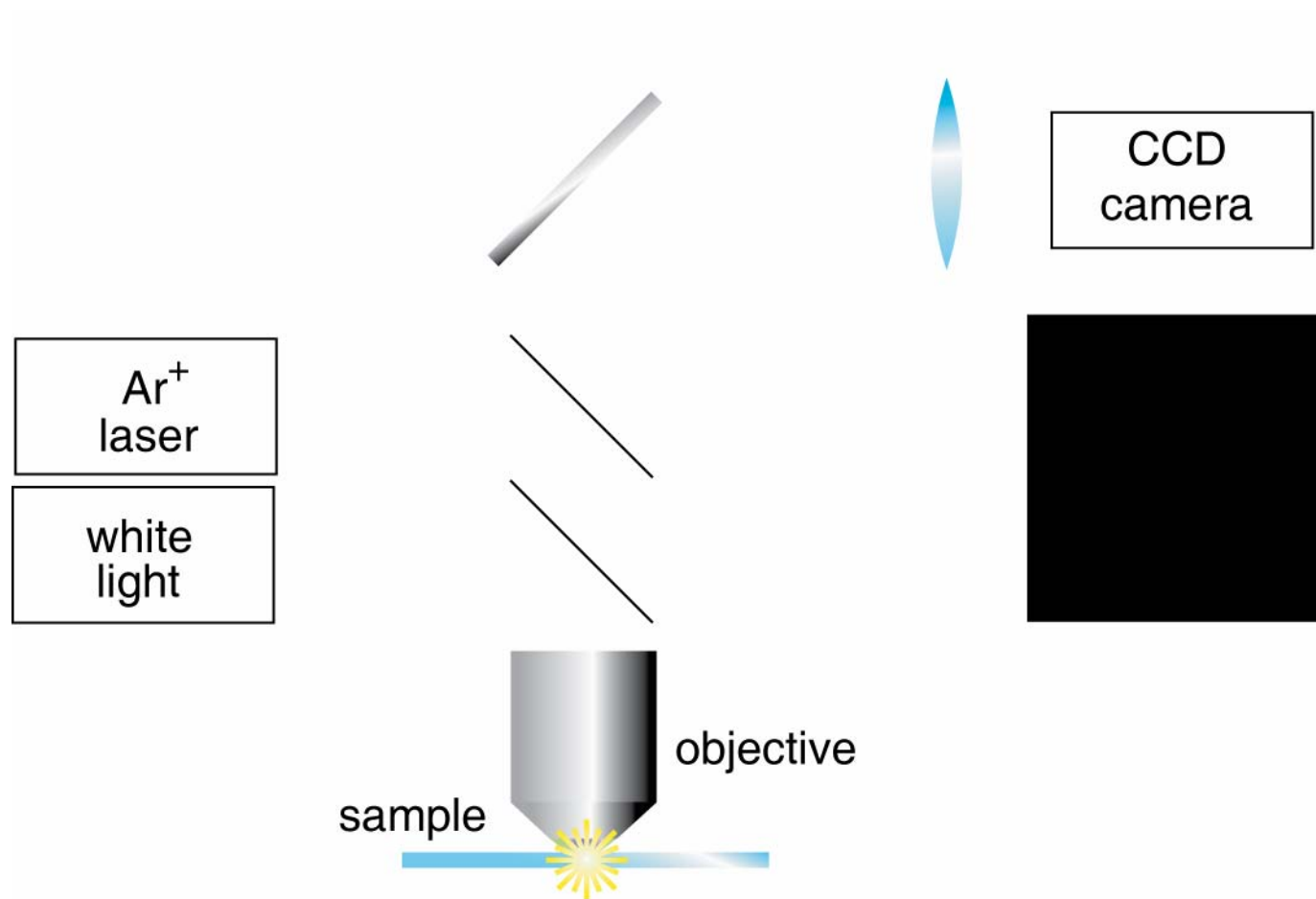


Fluorescence
Electro Luminescent
Conductive

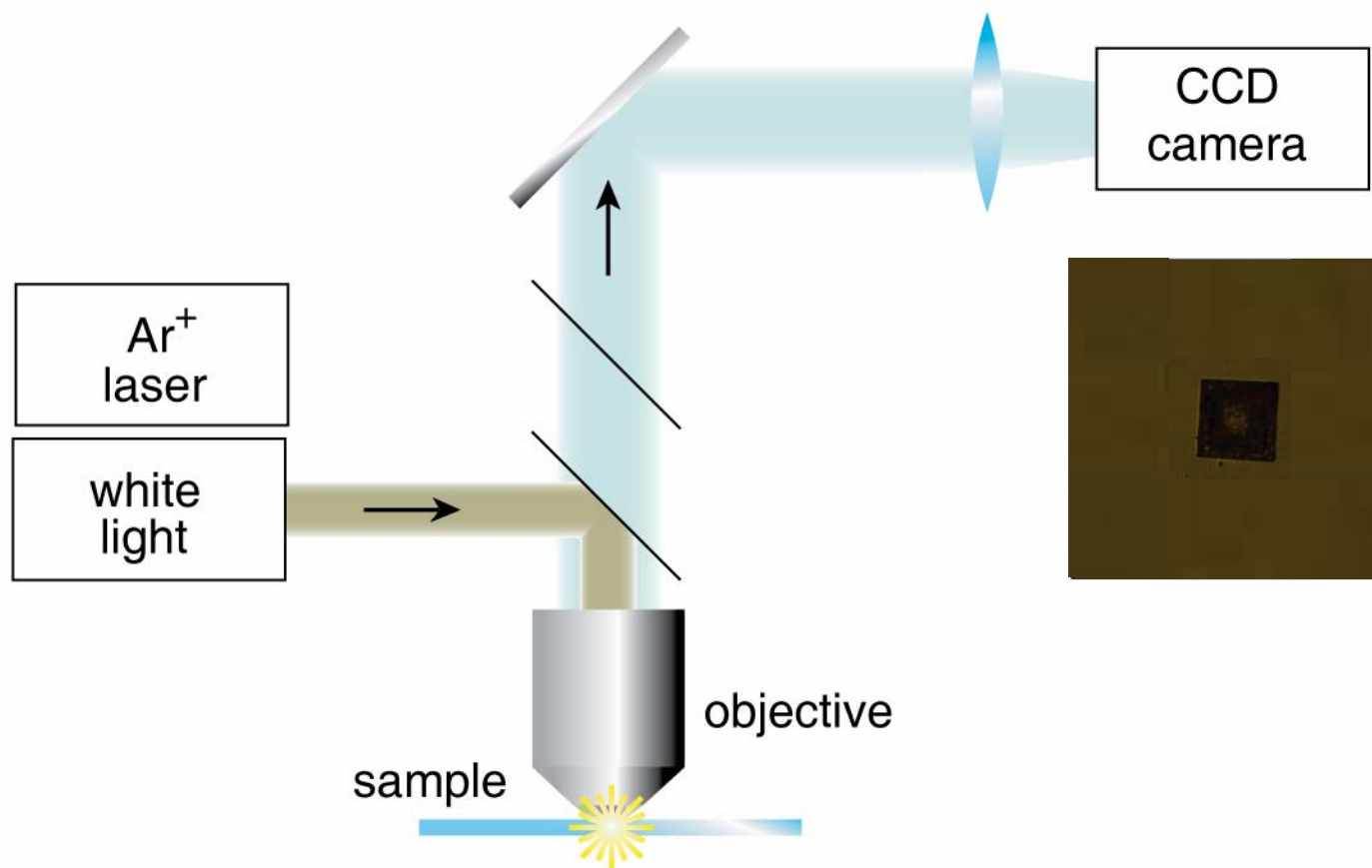
Microstructure containing MEH-PPV



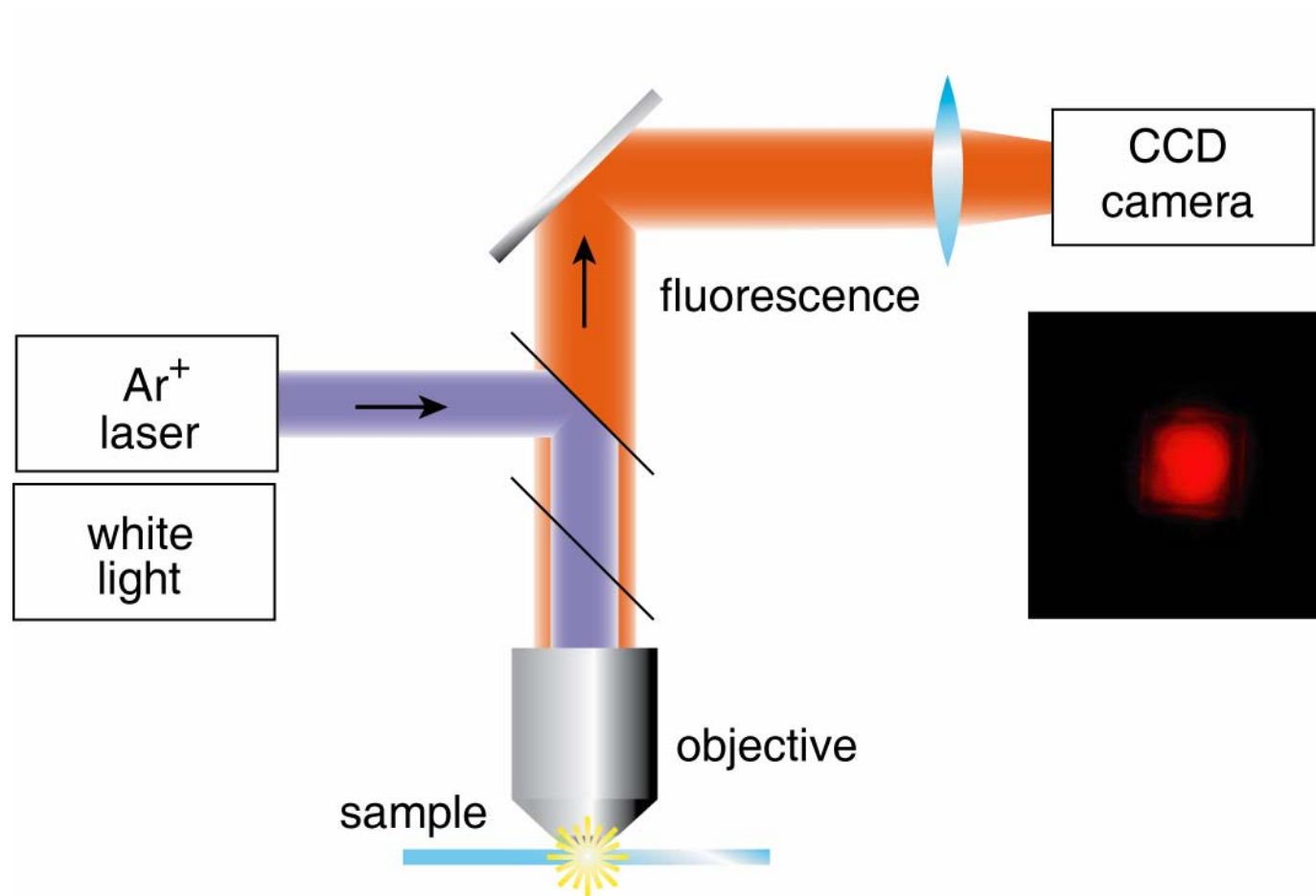
Microstructure containing MEH-PPV



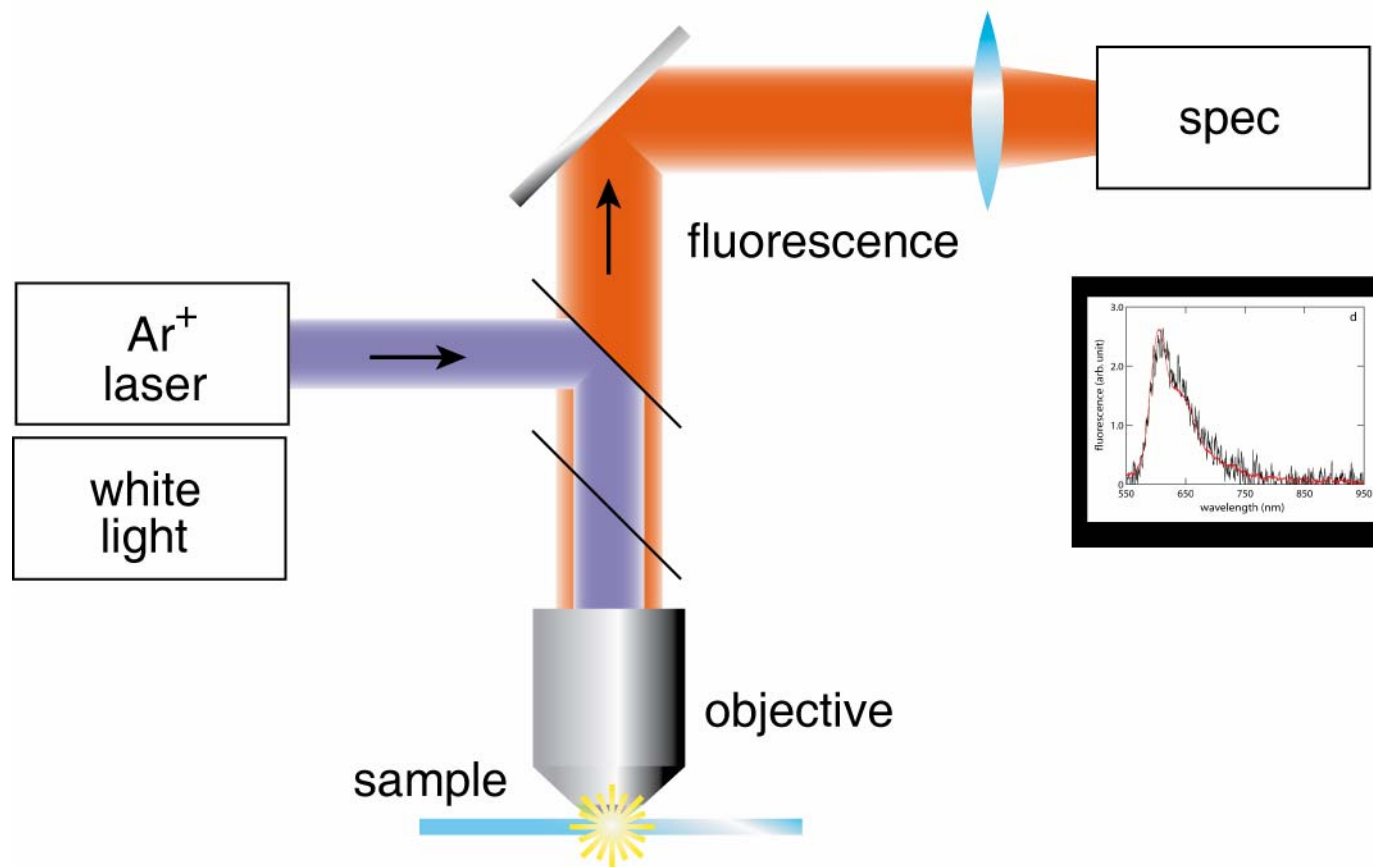
Microstructure containing MEH-PPV



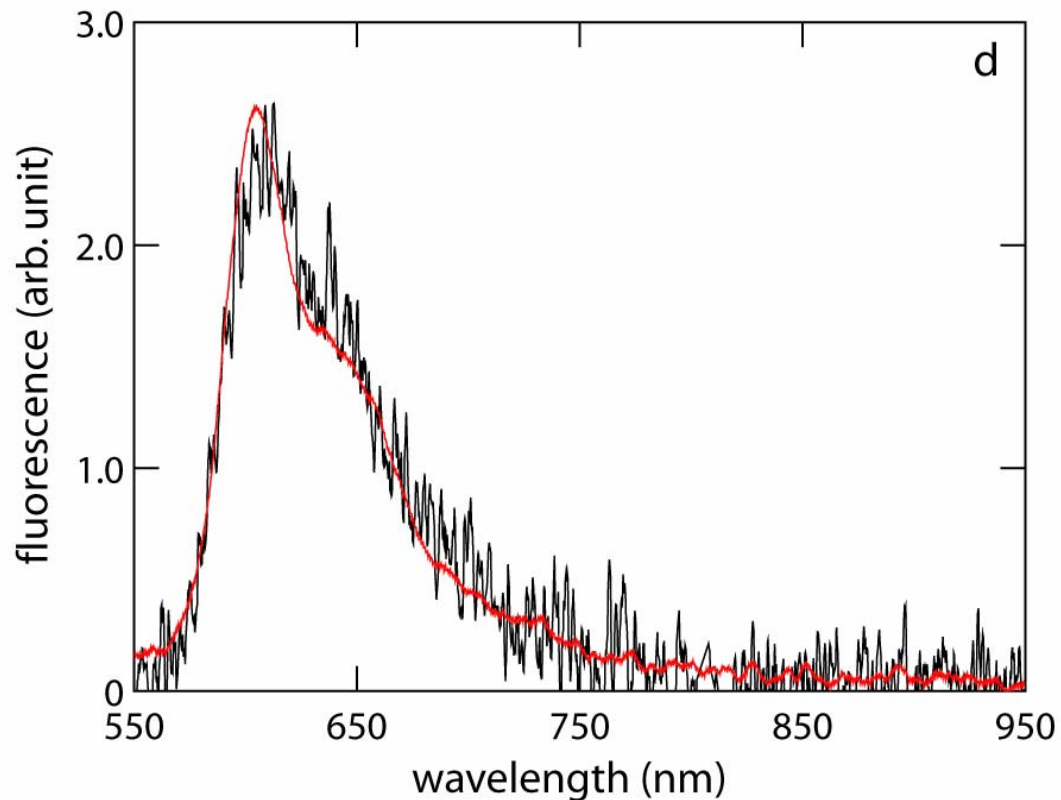
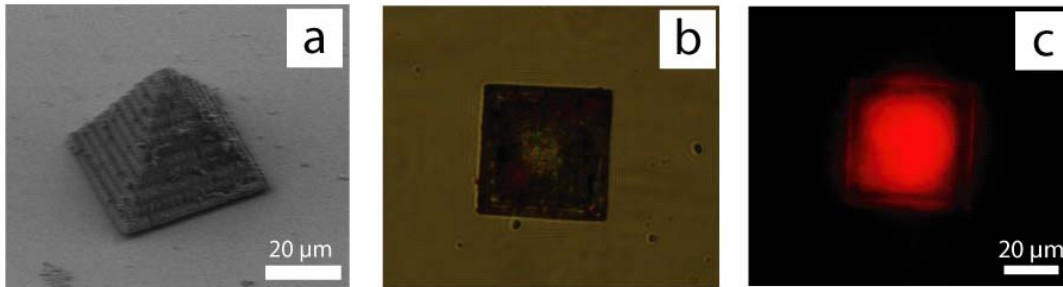
Microstructure containing MEH-PPV



Microstructure containing MEH-PPV



Microstructure containing MEH-PPV

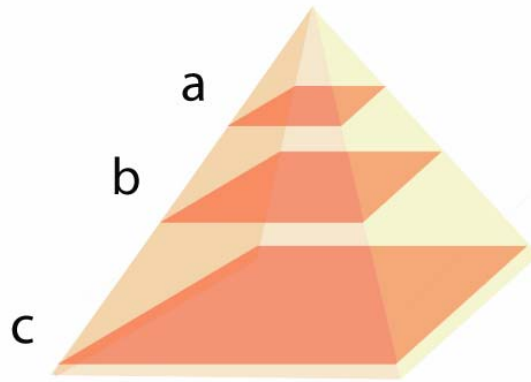


(a) Scanning electron microscopy

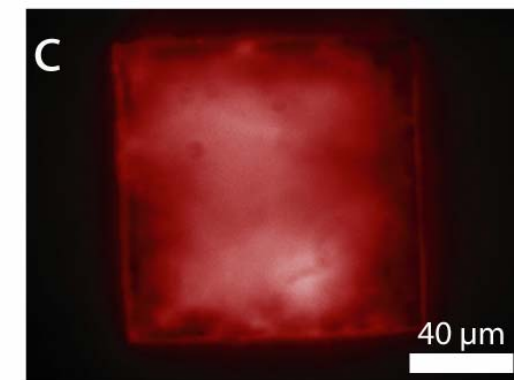
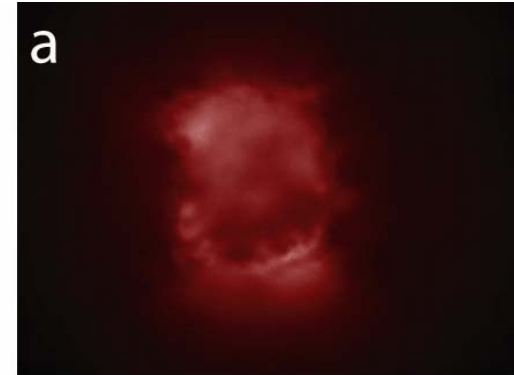
(b,c) Fluorescence microscopy of the microstructure with the excitation OFF (b) and ON (c)

(d) Emission of the microstructure (black line) and of a film with the same composition (red line)

Microstructure containing MEH-PPV



Fluorescent confocal microscopy images in planes separated by 16 μm in the pyramidal microstructure.



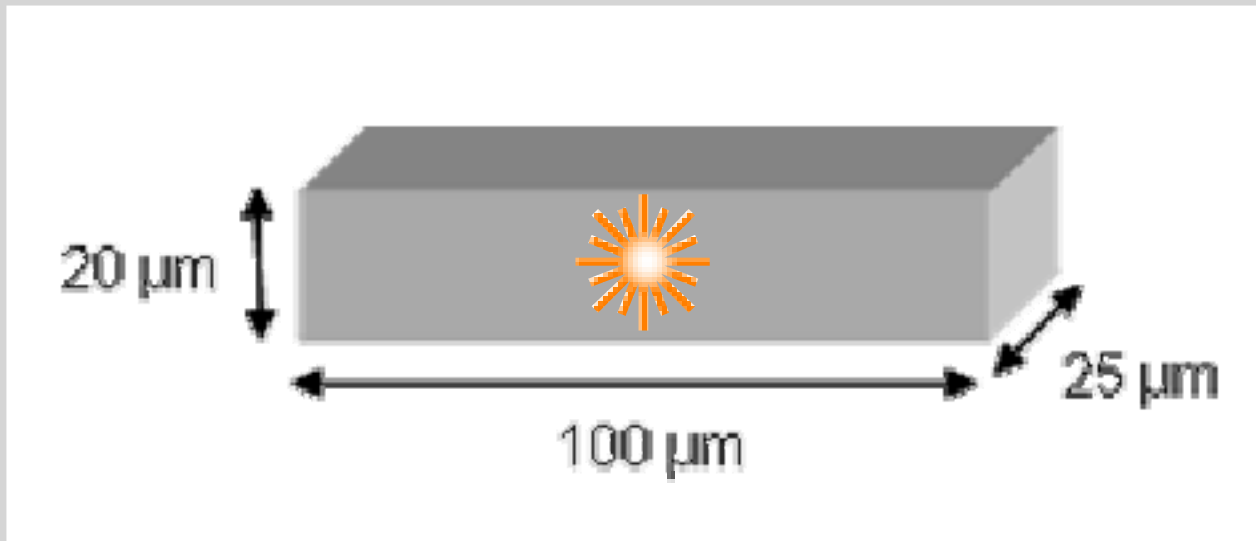
Microstructure containing MEH-PPV

Do we have waveguiding in the microstructure ?

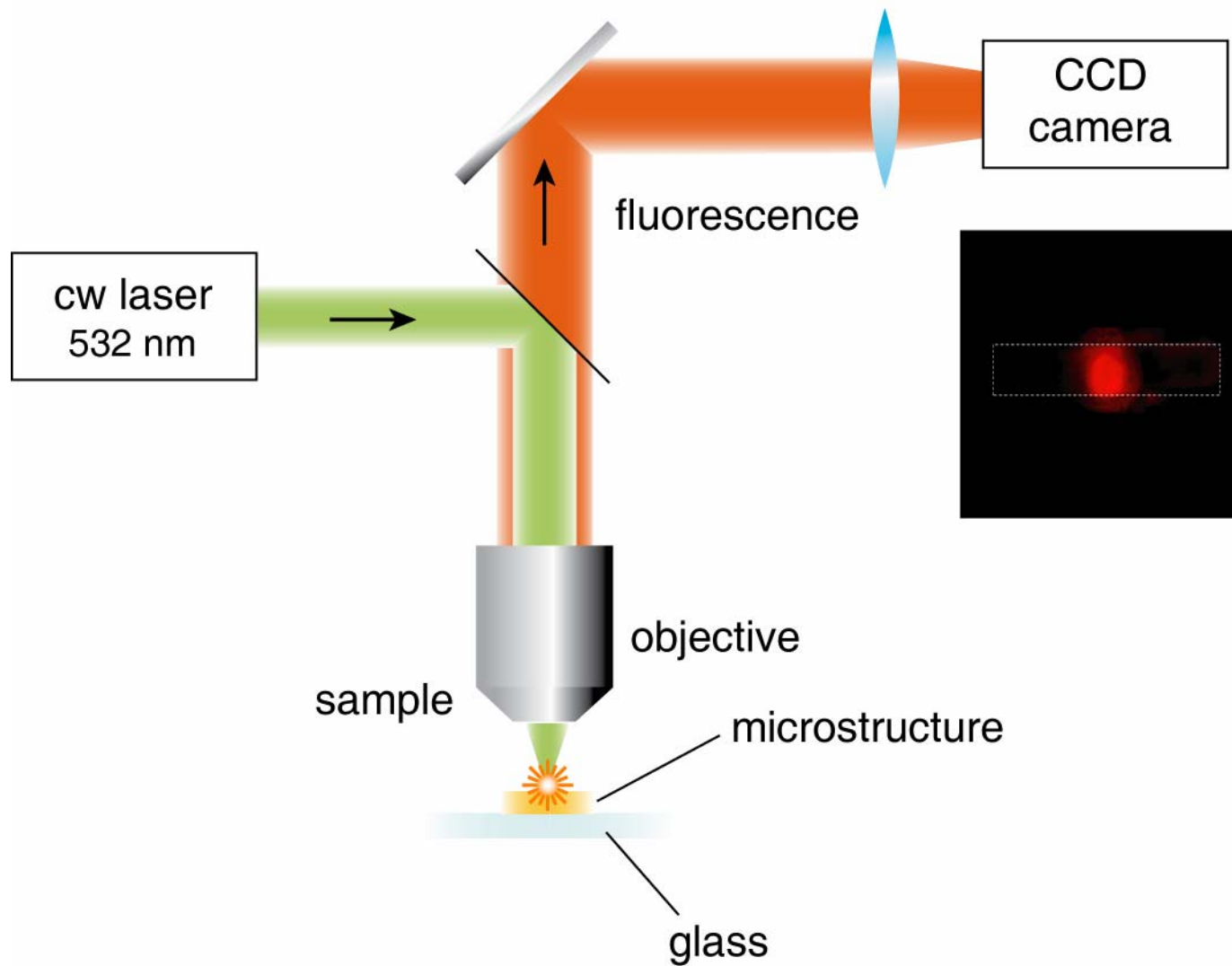


Microstructure containing MEH-PPV

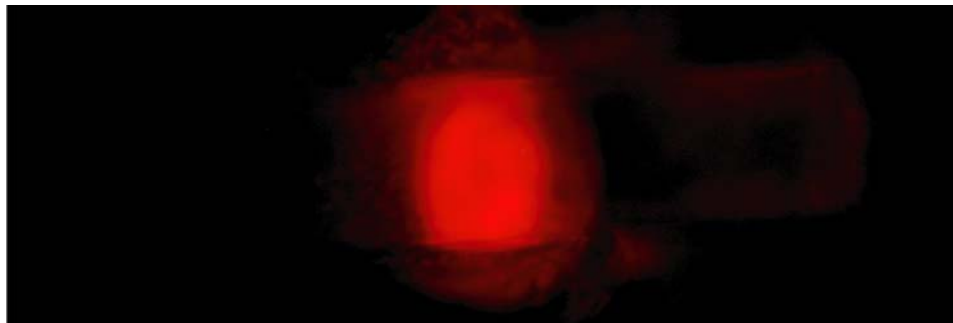
Do we have waveguiding in the microstructure ?



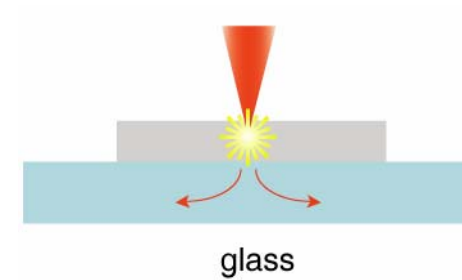
Microstructure containing MEH-PPV



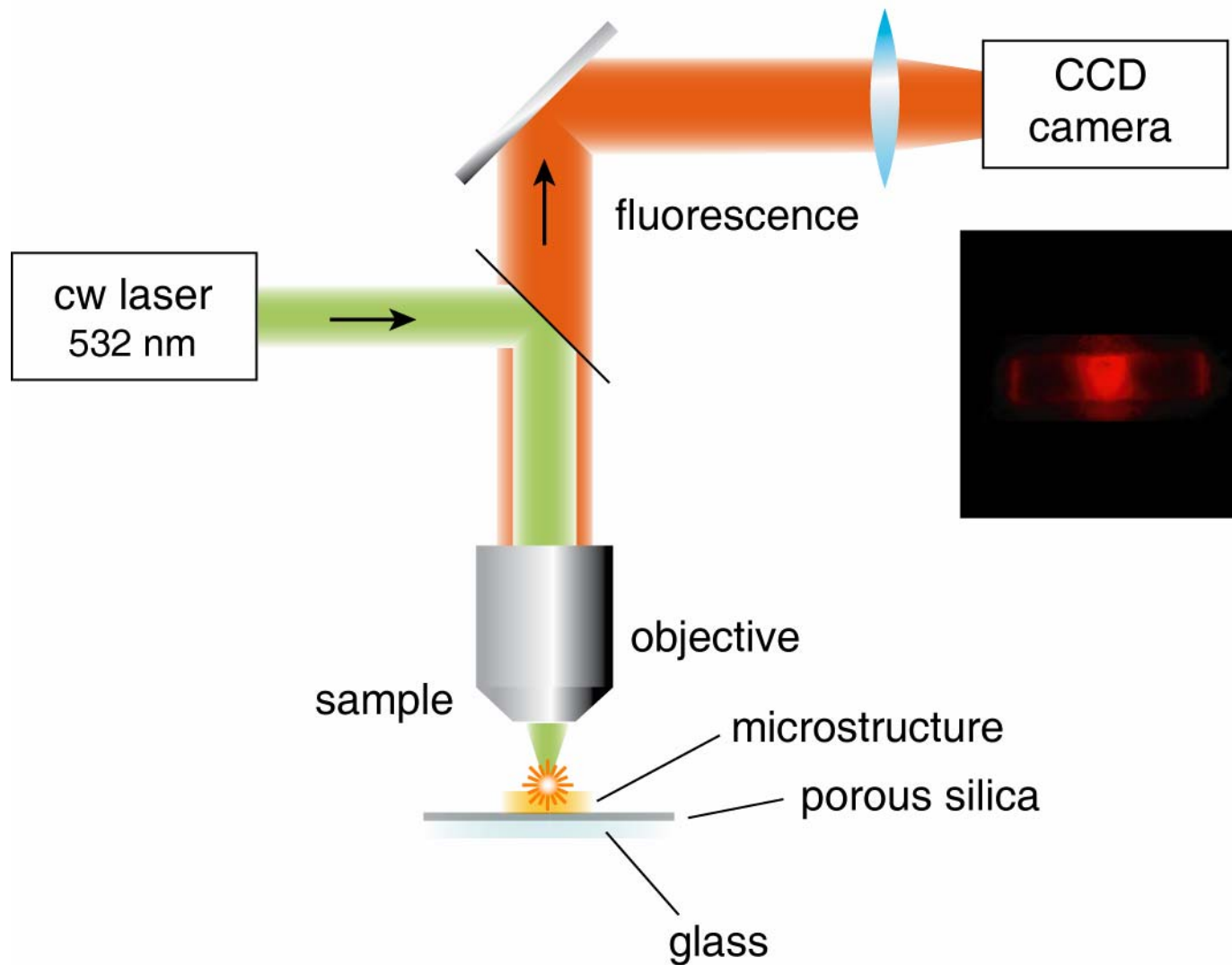
Microstructure containing MEH-PPV



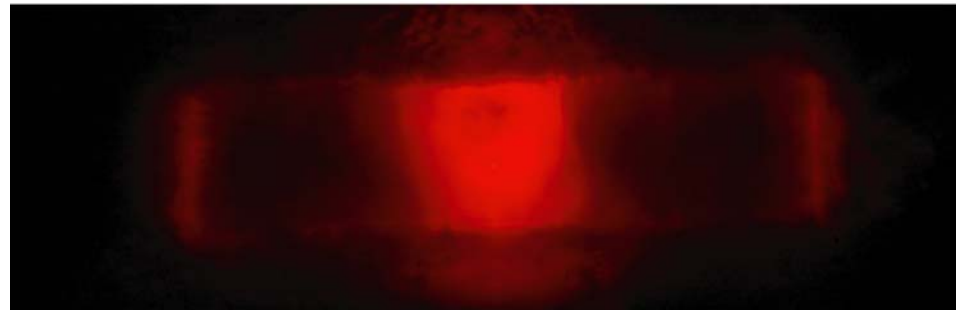
$20\ \mu\text{m}$ 



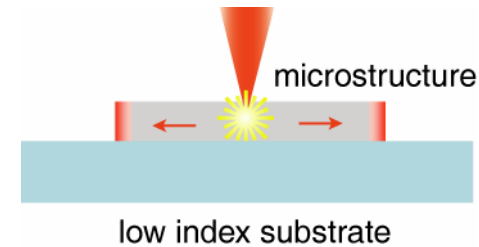
Microstructure containing MEH-PPV



Microstructure containing MEH-PPV



20 μm 

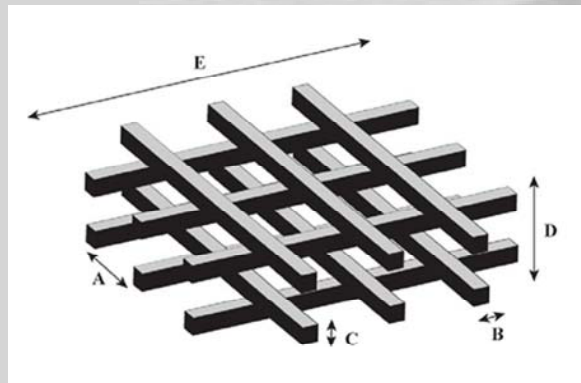


waveguiding of the microstructure fabricated on porous silica substrate ($n= 1.185$)

Applications: micro-laser; fluorescent microstructures; conductive microstructures

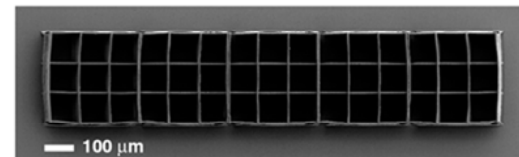
3D cell migration

- 3D cell migration studies in micro-scaffolds



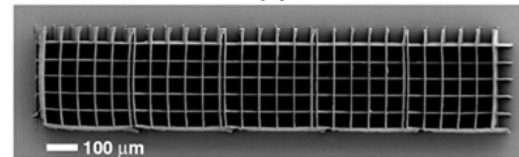
SEM of the scaffolds

110 μm pore size



(c)

52 μm pore size



(d)

Top view



(e)

(f)

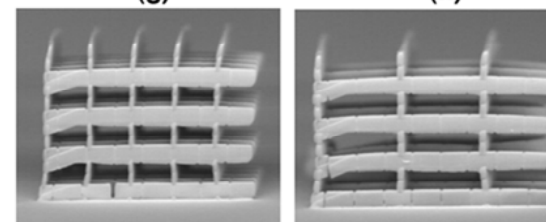
110, 52, 25, 12 μm pore size



(g)

(h)

Side view



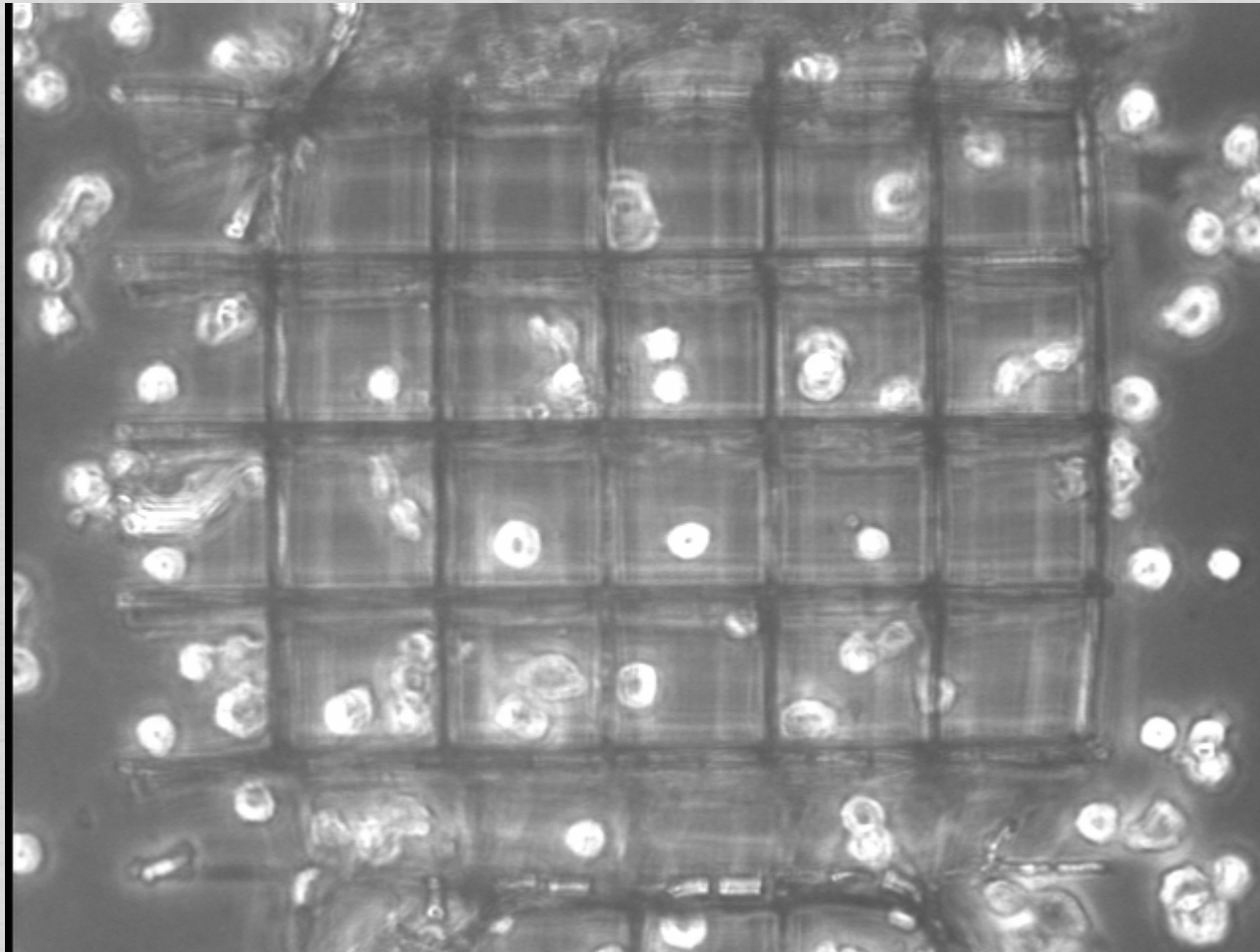
(i)

(j)

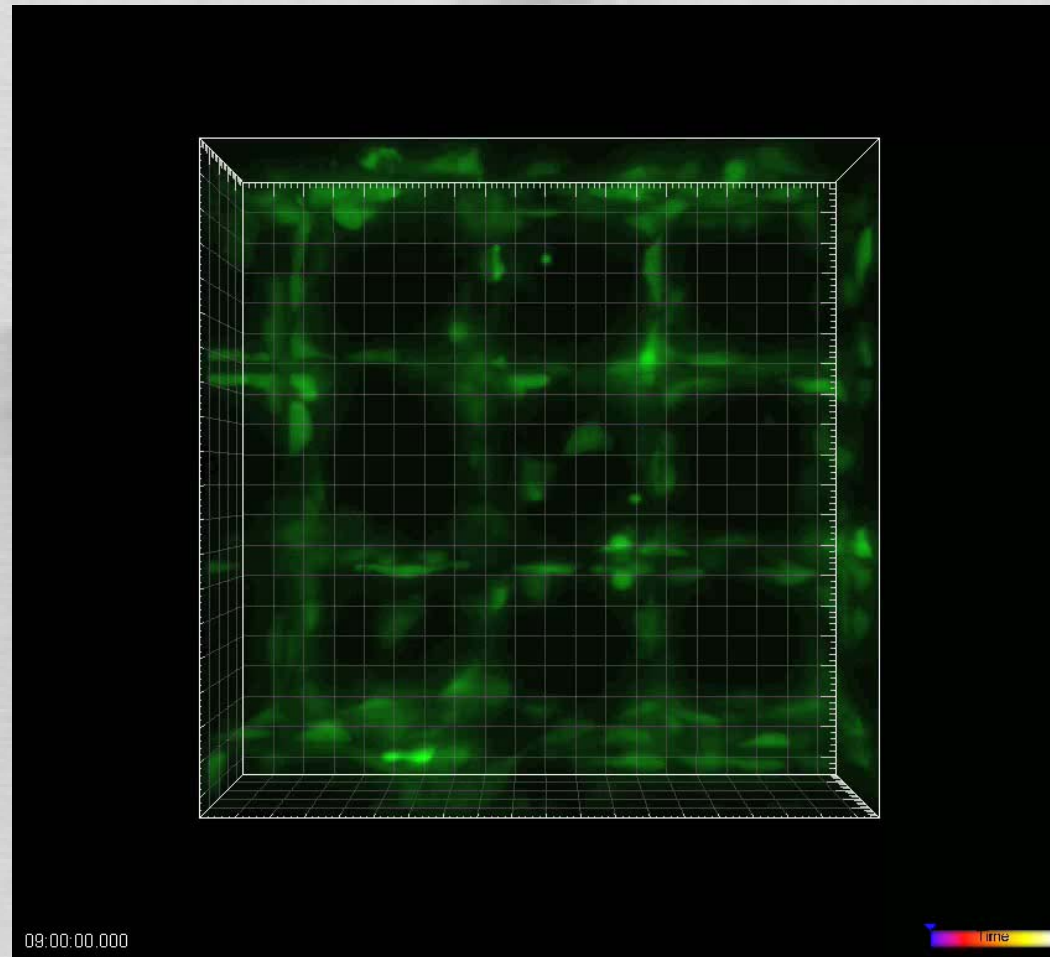
25, 52 μm pore size

3D cell migration

50 μm pore size

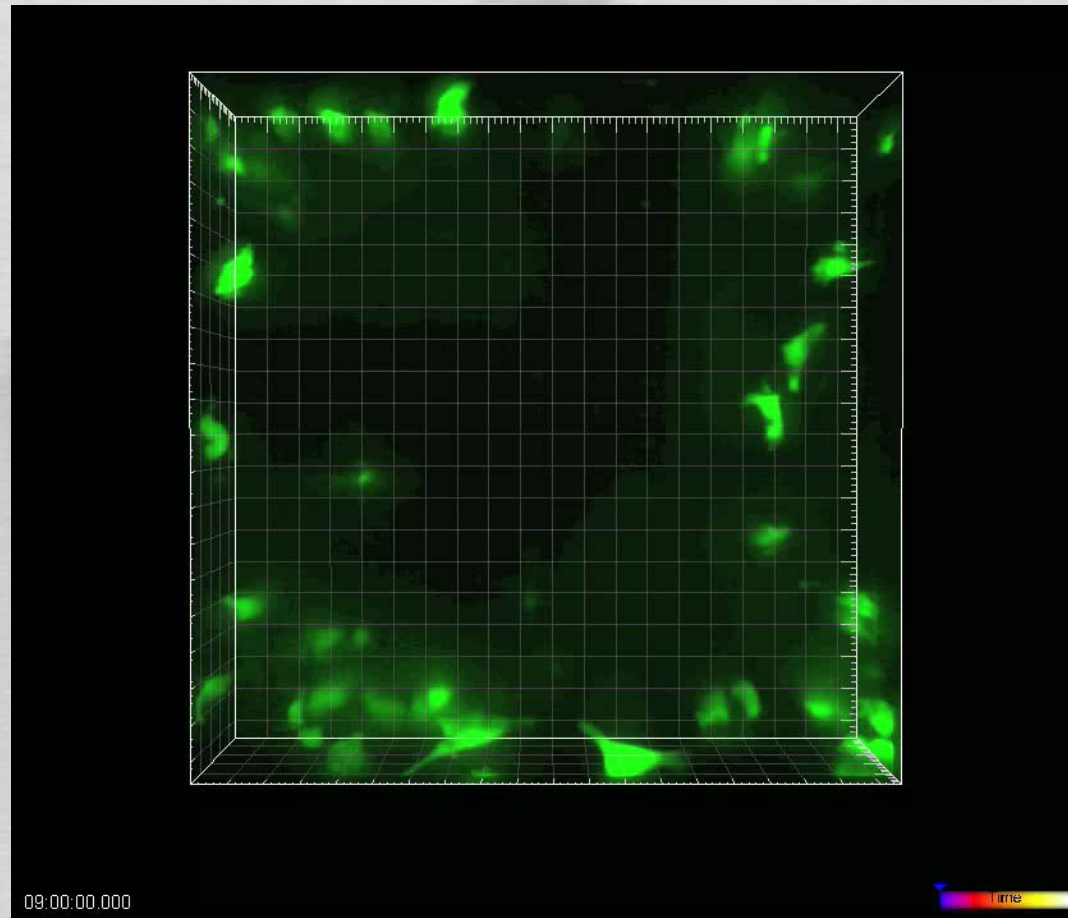


3D cell migration



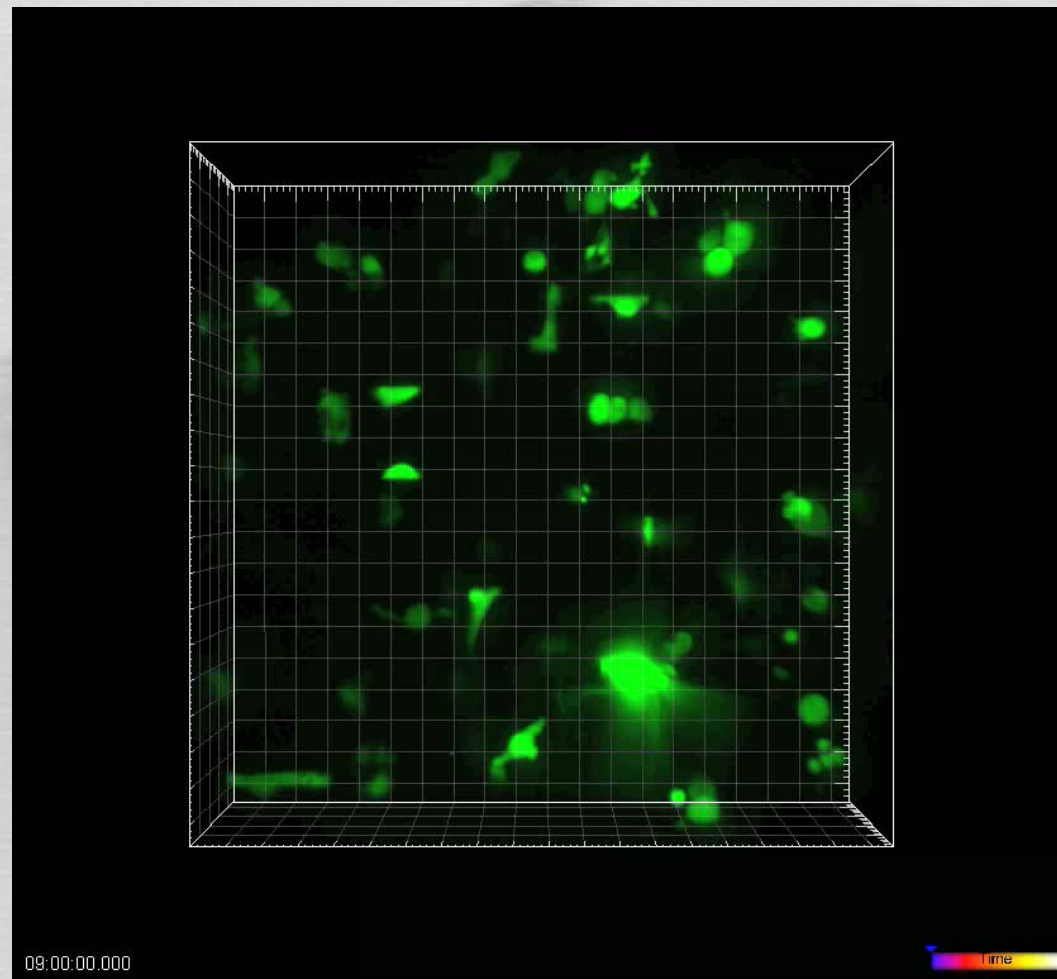
110 μm pore size

3D cell migration



12 μm pore size

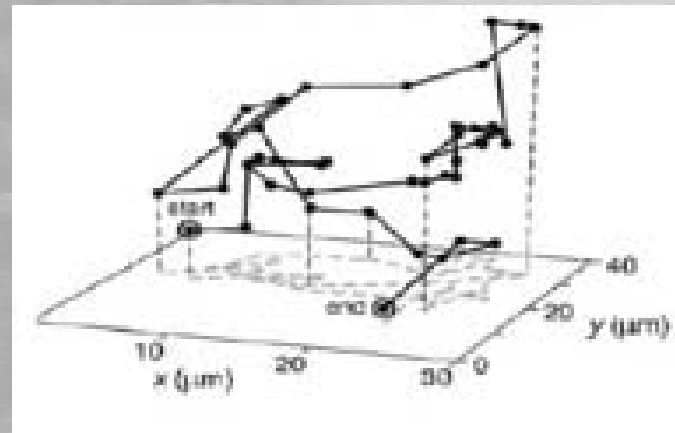
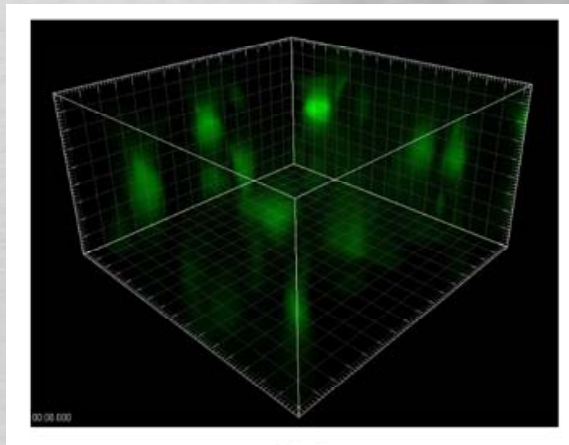
3D cell migration



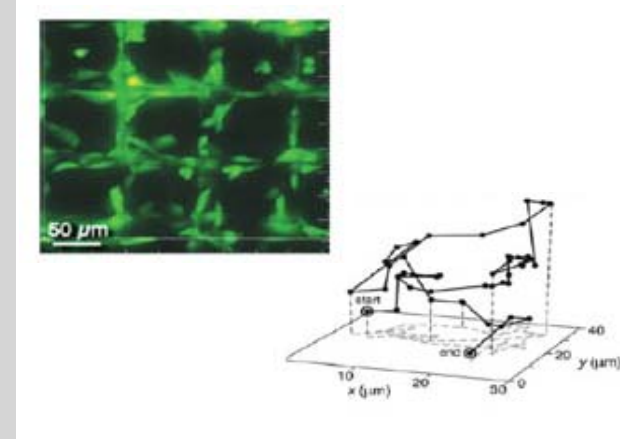
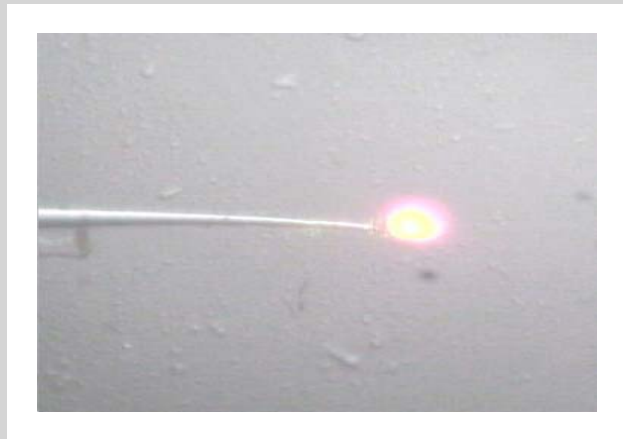
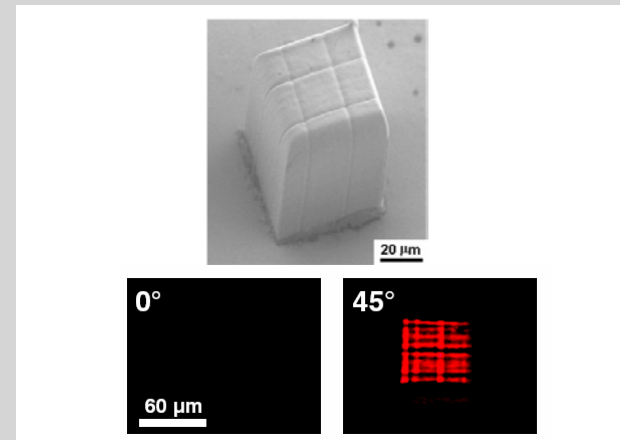
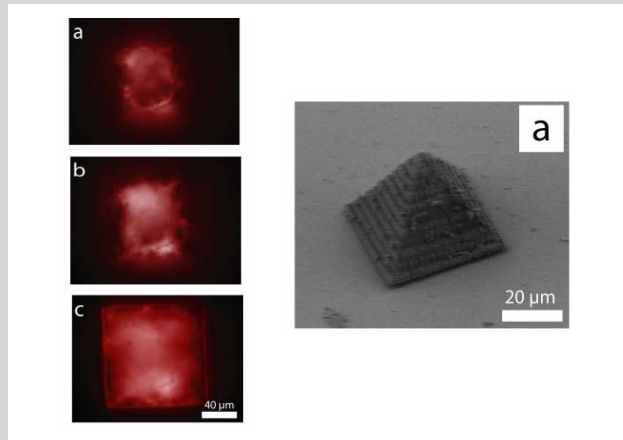
52 μm pore size

3D cell migration

- 3D cell migration studies in micro-scaffolds



Summary



Acknowledgments

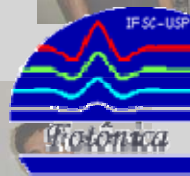
FAPESP
CAPES
CNPq

NSF
ARO

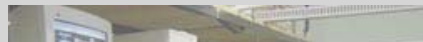
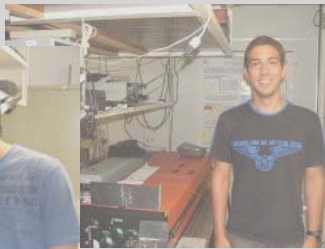
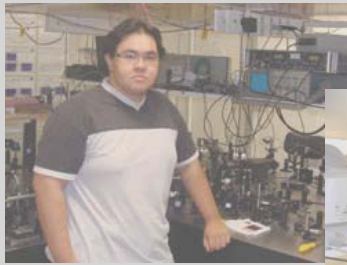
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Thank you !



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